



# Photocathodes for Polarized Electron Beams at Jefferson Lab

**Marcy Stutzman**  
**December 3, 2021**

Thomas Jefferson National Accelerator Facility is managed by  
Jefferson Science Associates, LLC, for the U.S. Department of Energy's Office of Science



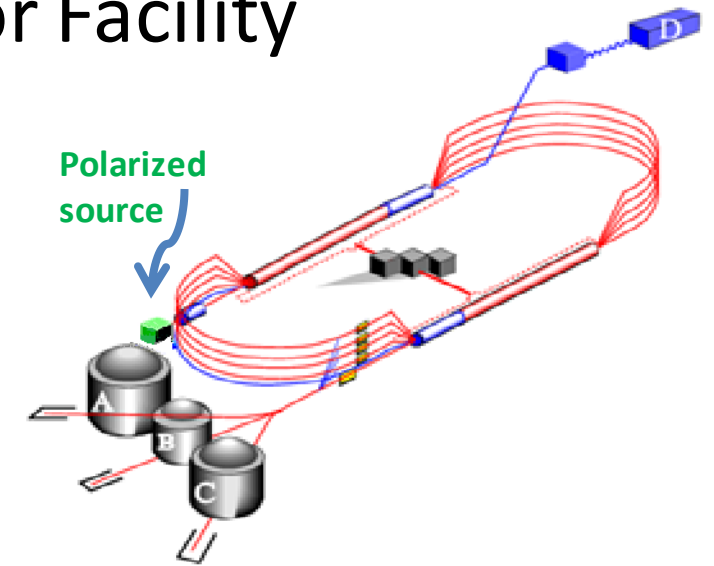
# Outline

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- Jefferson Lab, EIC and polarized electrons
- Photoemission from GaAs
- High polarization photocathodes
  - Structure
  - Supply chain issues
  - Initiatives for new growth methods
- Photocathode damage mechanisms
  - Ion acceleration
  - Vacuum improvements
  - Damage evaluation
- Novel ideas for photocathodes
- Conclusions

# CEBAF at Thomas Jefferson National Accelerator Facility

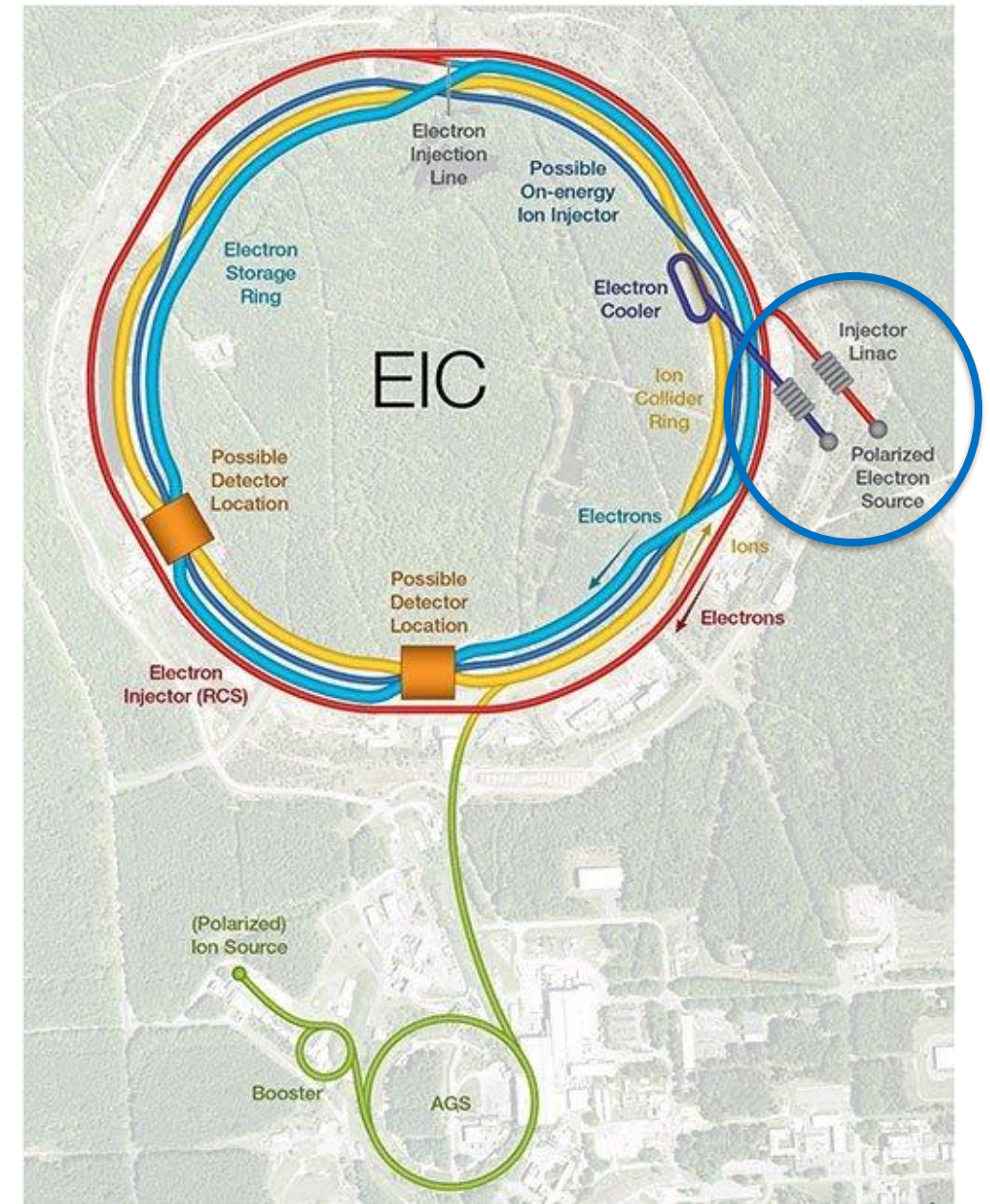
- 12 GeV electron accelerator for Nuclear Physics (DOE)
- Mission: To understand the transition from hadronic (protons and neutrons) to partonic (quarks and gluons) physics.
  - Electron beam, with polarization nearly 90% and current to 200  $\mu\text{A}$
  - Investigate spin dependent nuclear processes
  - ~1 mile racetrack design accelerator
  - 4 experimental halls





# Polarized electrons for EIC

- Electron Ion Collider
  - Next major DOE NP project
  - Location: Brookhaven Natl. Lab
  - BNL RHIC tunnel: 2.4 mile circumference
  - Add polarized electron beam
    - New capability for BNL
- Physics motivation
  - *Strong nuclear force*
  - *Proton spin origin*
  - *Proton mass origin*



# Why do we need polarized electrons?

- Nuclear physics electron scattering
  - Parity violation: differences in scattering rate between electron and nuclear spin states
    - QWeak →
    - HAPPEX, PREX, CREX
    - MOLLER
  - Proton spin structures
    - Nature Physics **17**, p.736 (2021)
  - Nucleon electromagnetic structure
    - Nature **566**, p.354 (2019) →

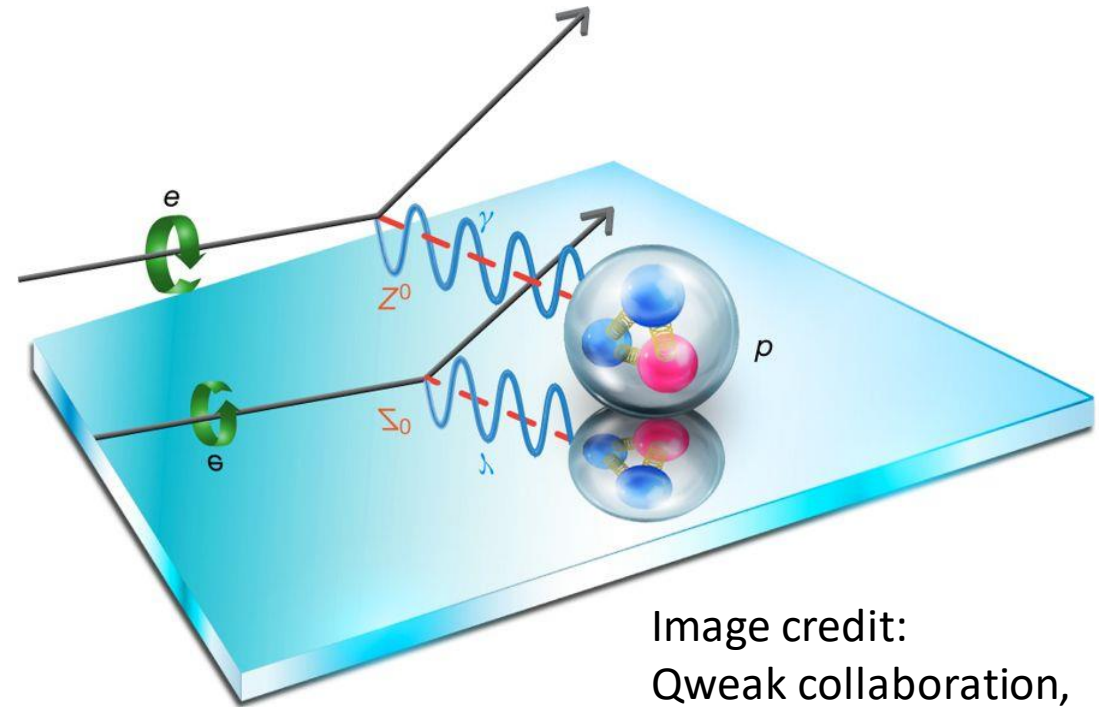
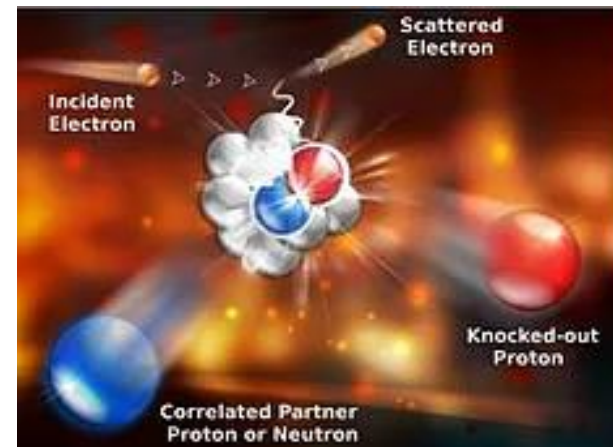
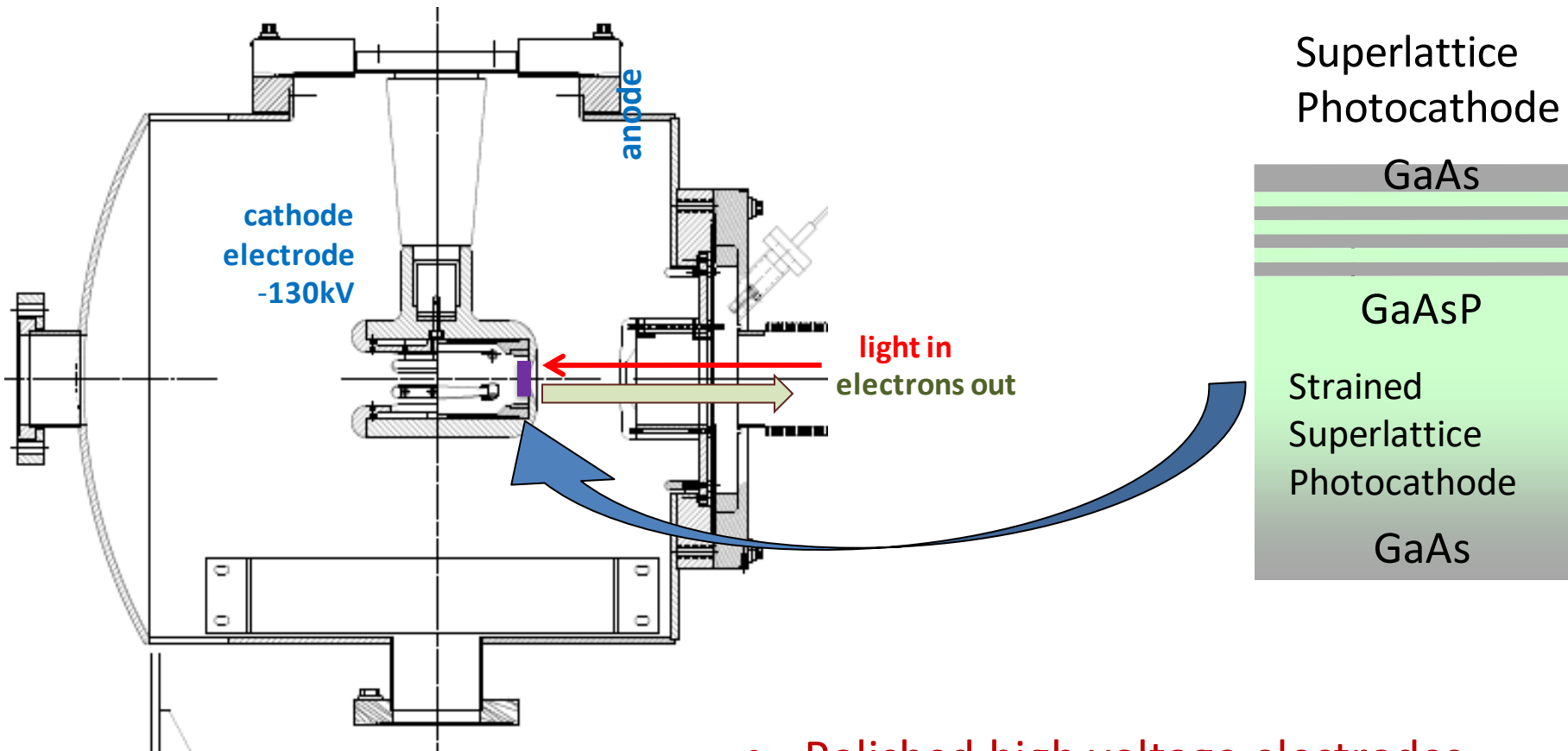


Image credit:  
Qweak collaboration,  
*Nature* **557**, p207 (2018).



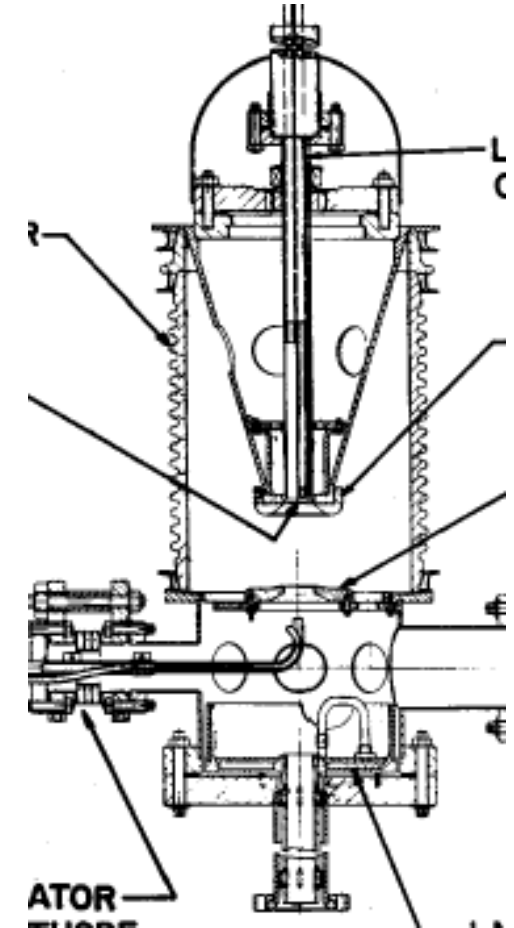
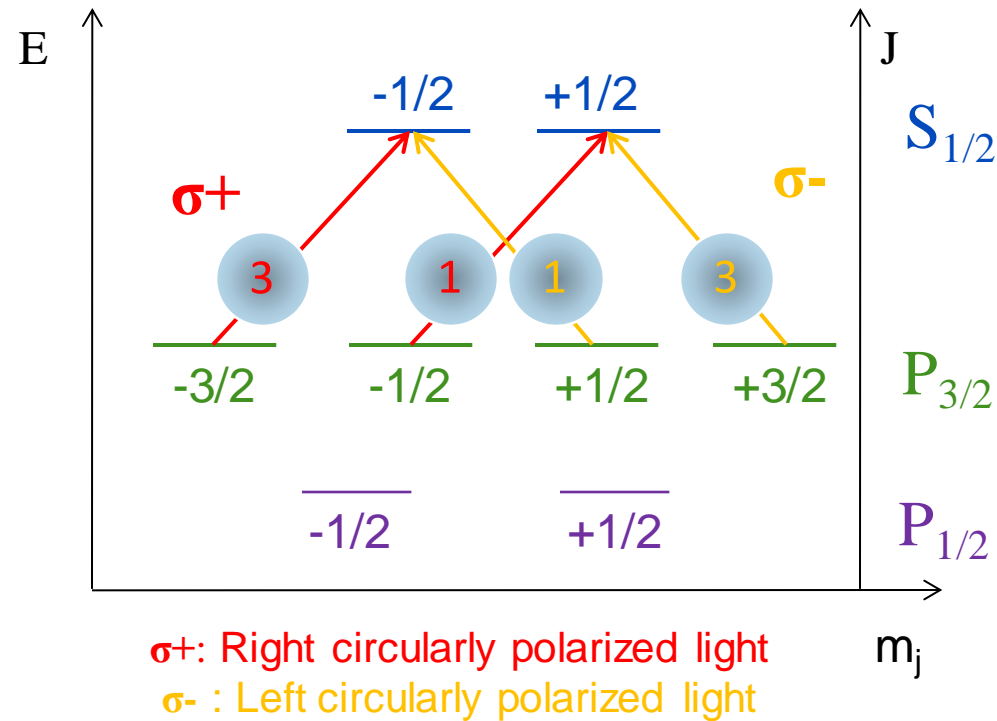
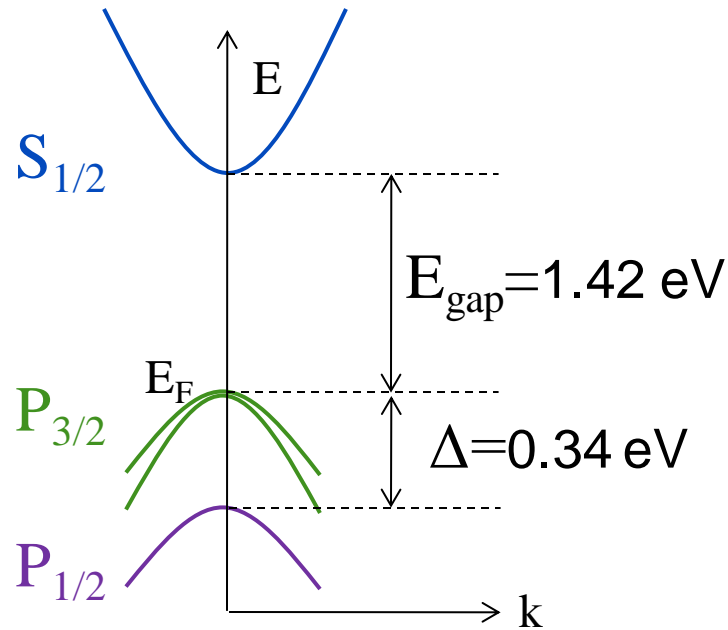
# DC Photoemission Source



- Polished high voltage electrodes
- Strained superlattice GaAs/GaAsP photocathode
- Surface preparation: Cs, oxygen or fluorine
- Base pressure approaching XHV  $\equiv P < 1 \times 10^{-10}$  Pa



# Spin Polarized Photoemission from Bulk GaAs



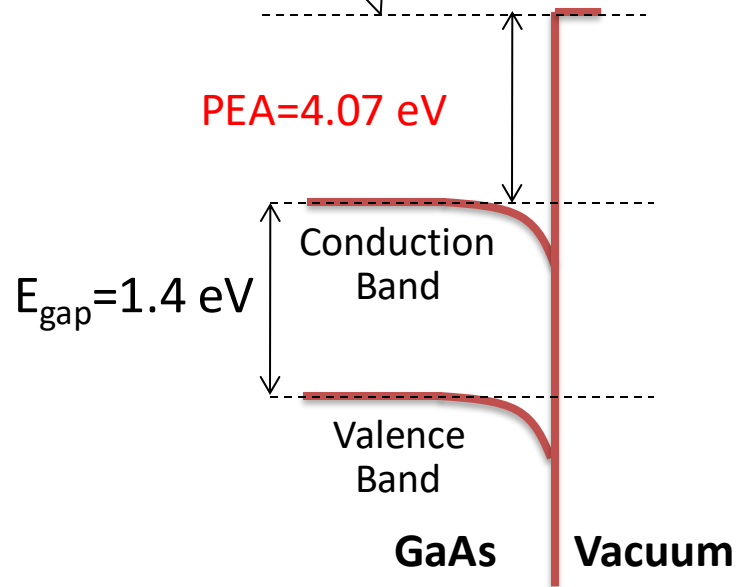
SLAC 1977

Note: Flip electron spin using laser polarization. Rate 30-1000 Hz

# Photoemission from GaAs

## Bare GaAs surface

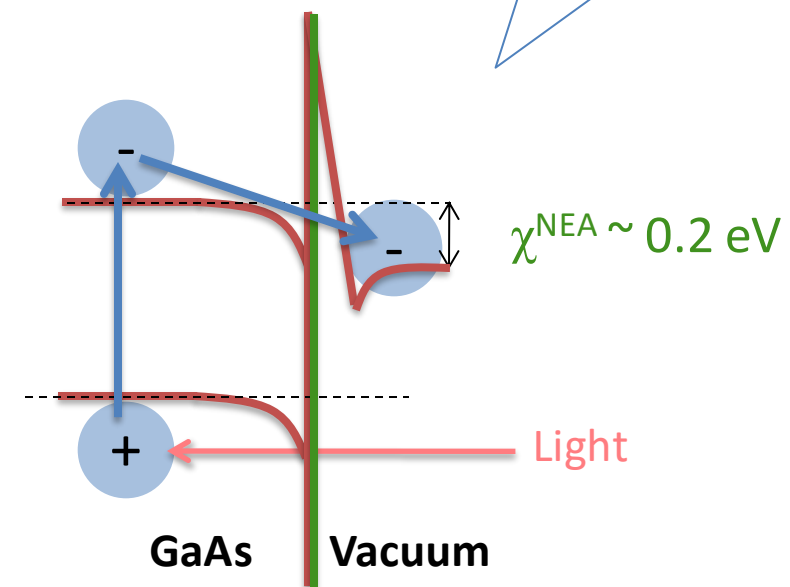
- Large Work Function
- Positive Electron Affinity (PEA)



NEA Surface Activation

## Dipole layers of Cs + $\text{NF}_3$ or Oxygen

- Reduces Work Function
- Negative Electron Affinity (NEA)

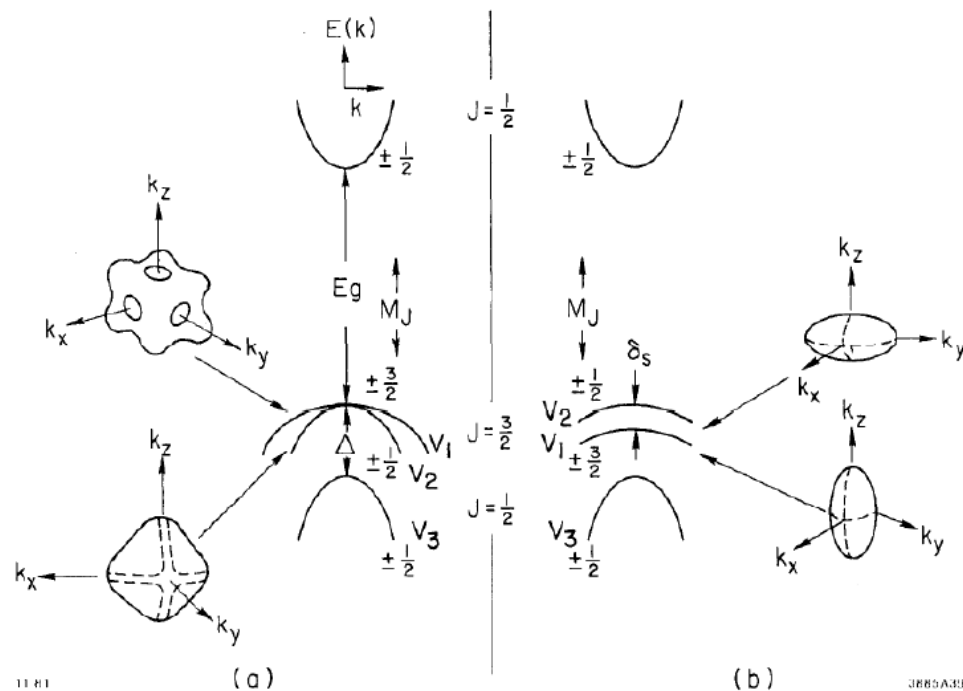


GaAs Spin Polarized Electron Source, D.T. Pierce, R.J. Celotta, G.-C. Wang, W.N. Unertl, A. Galejs, C.E. Kuyatt, and S.R. Mielczarek, Review of Scientific Instruments 51(4), 478 (1980).



## Breaking the 50% barrier

PhD thesis, Paul Zorabedian, SLAC Report 248, 1982



Application of a uniaxial strain removes the degeneracy of the  $P_{3/2}$  state

## Eliminate degeneracy of $P_{3/2}$ state via “Interface Stress Method”

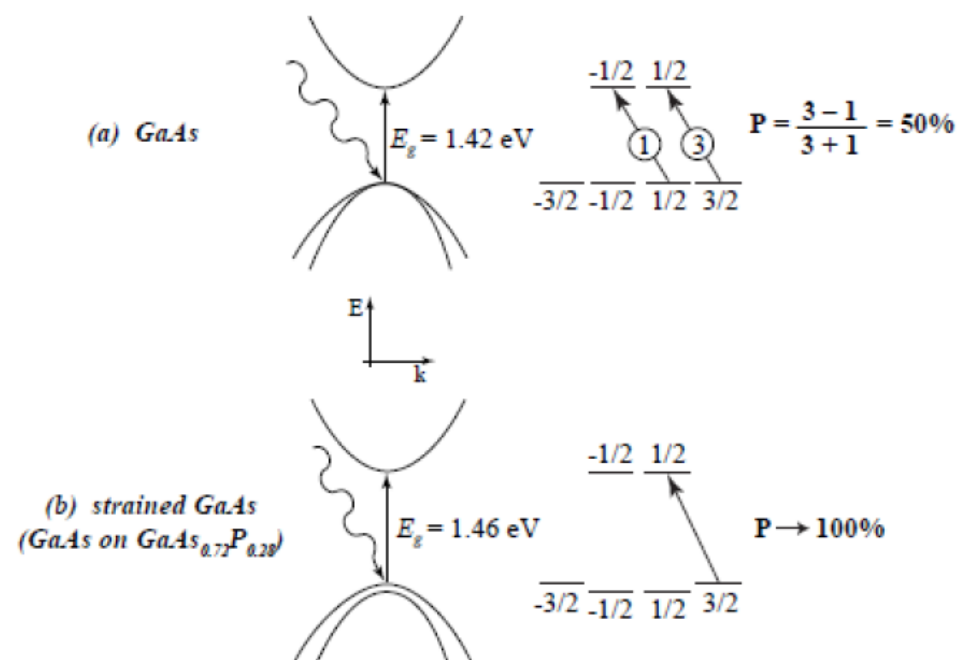
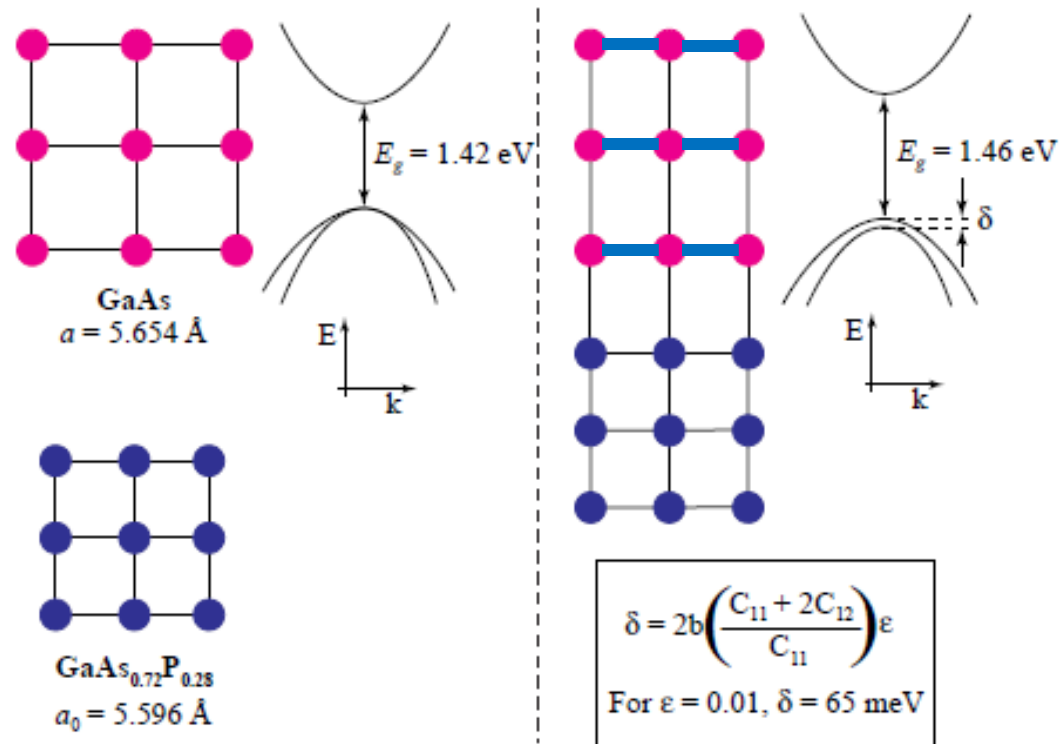


Image from Pablo Saez, PhD Thesis, Stanford University, SLAC Report 501, 1997

# Breaking the P=50% barrier

## Lattice mismatch provides stress

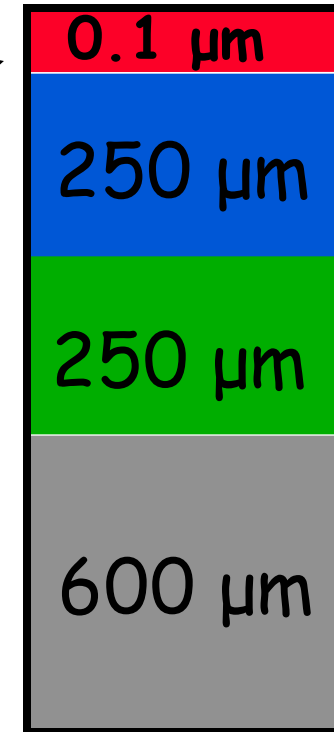
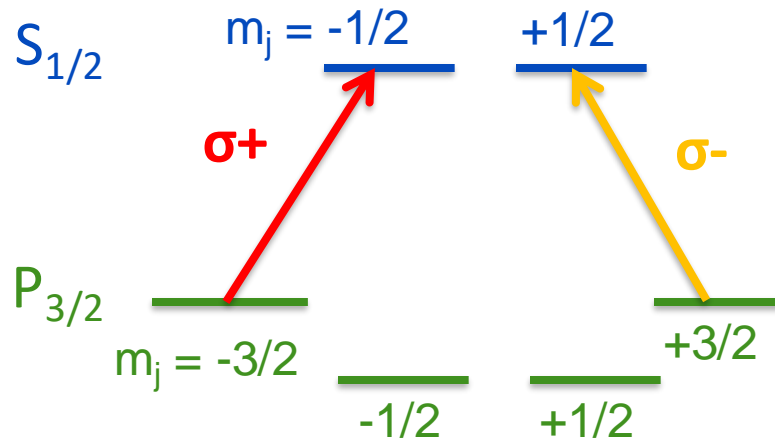


- The band gap of the substrate layer must be larger than surface layer
- Lattice constants must differ enough to introduce suitable strain
- Adjust lattice constant of substrate by varying concentration of third element

1% lattice mismatch provides equivalent force as hydraulic press!

Pablo Saez, PhD Thesis, SLAC Report 501, 1997

# Strained layer GaAs



Strained GaAs

$\text{GaAs}_{1-x}\text{P}_x$  ( $x=0.29$ )

$\text{GaAs}_{1-x}\text{P}_x$  ( $0 < x < 0.29$ )

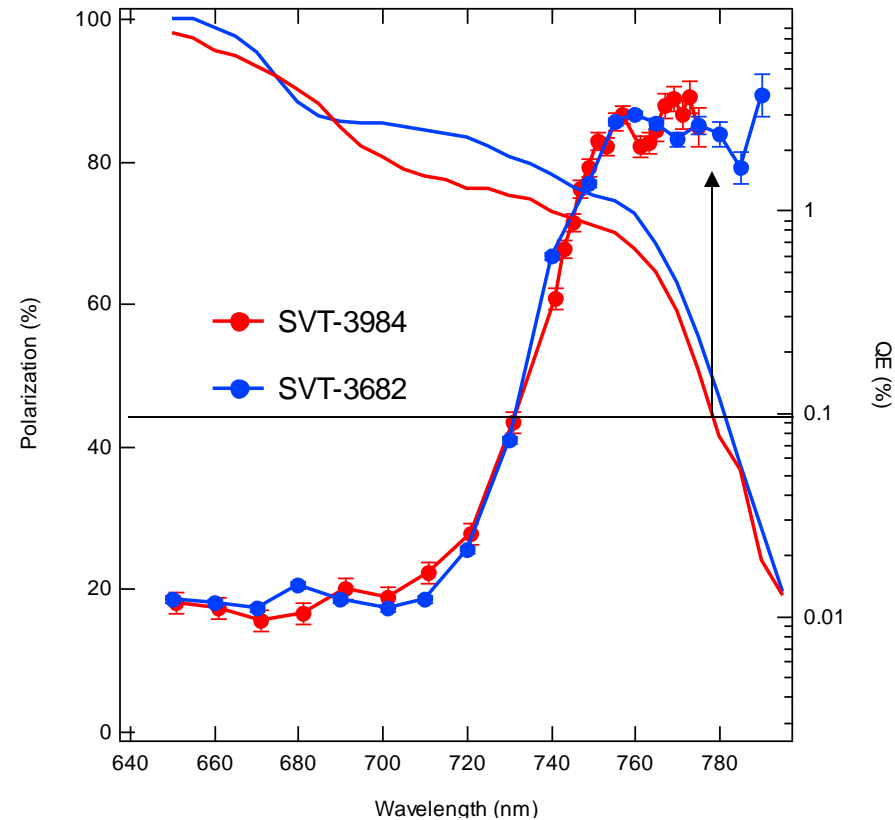
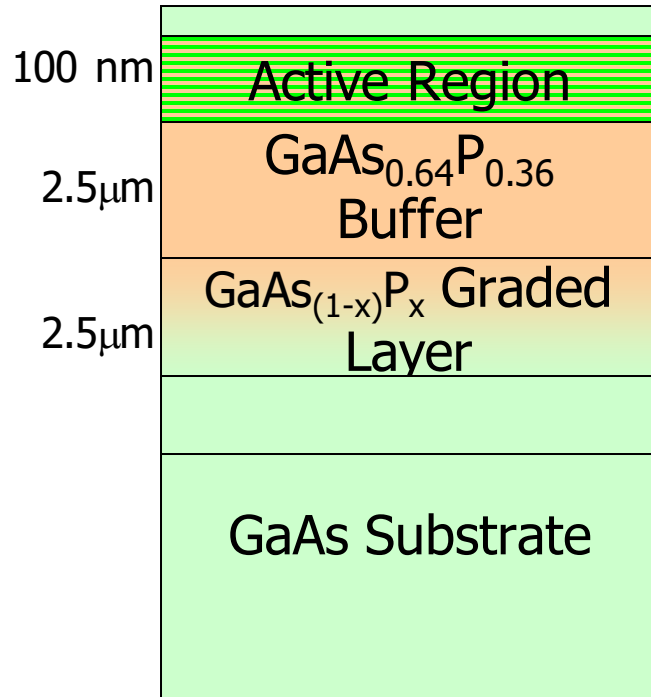
p-type GaAs  
substrate

- ✓ Polarization 75%  $\gg$  50% ☺
- ✓ Strain relaxes in 100 nm layer
- ✓ QE 0.1%

MOCVD-grown epitaxial  
spin-polarizer wafer

Maruyama et al., Phys. Rev. B, **46** 4261 (1991)

# Strained layer superlattice GaAs/GaAsP



D. Luh et al, SLAC, PESP2002

QE 1% and Polarization 85%

From Aaron Moy, SVT Assoc and SLAC, PESP2002



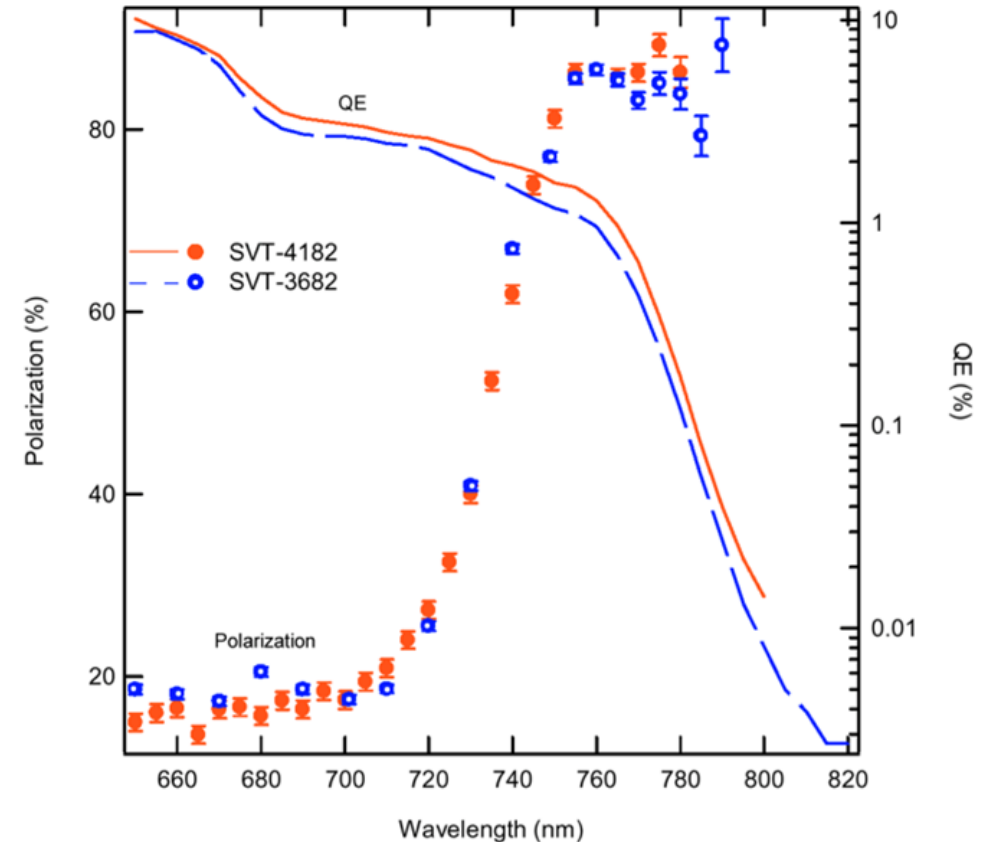


# Innovation through SBIR program

- SVT SBIR Partnerships with SLAC or JLab for high polarization photocathodes:
  - Phase I: 2001, 2005, 2007, 2012, 2013
  - Phase II: 2002, 2008, 2013, 2014
- Various Superlattice Structures
  - **GaAs/GaAsP**
  - GaAsSb
  - AlGaAs/GaAs
  - Distributed Bragg Reflector for high QE

## Variations

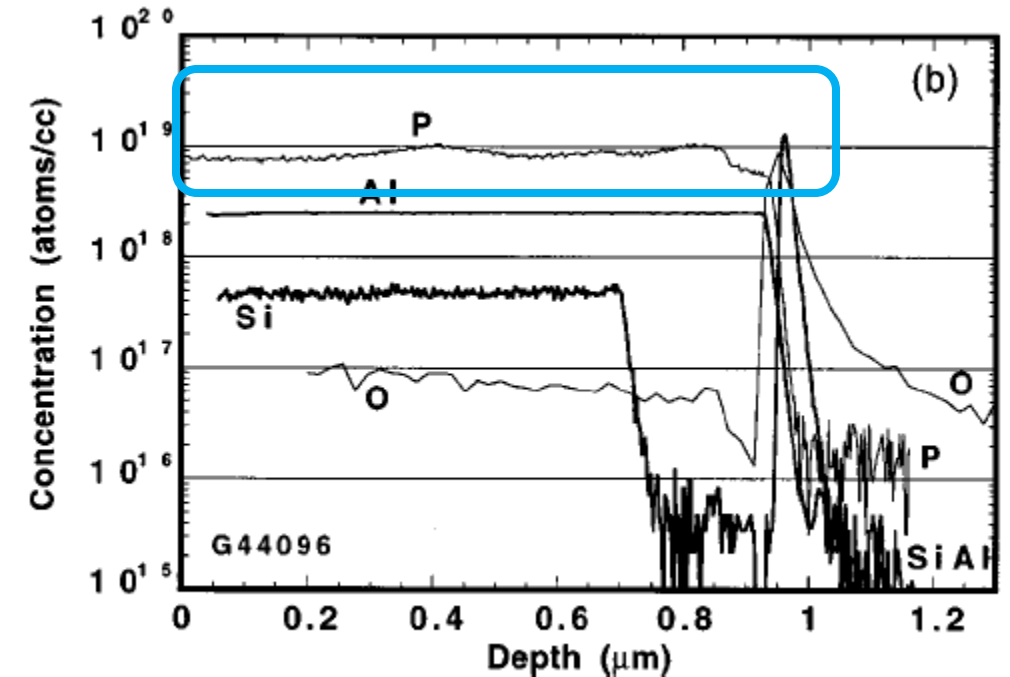
- Quantum Well thickness
- Barrier thickness
- Strain layer concentration
- Number of periods



AlGaAs/GaAs, A. Moy 2009

# Technical Challenges of Growing GaAs/GaAsP using GSMBE

- GSMBE (Gas source MBE) uses crackers for AsH<sub>3</sub> (arsine) and PH<sub>3</sub> (phosphine)
  - Both gasses Toxic, Flammable
  - Phosphorus grows on MBE walls
    - Generates phosphine gas & phosphoric acid when venting
    - Absorbs water and has high water vapor pressure when pumped back down
    - Residue cannot be scraped off - ignites
      - Careful degassing can solve this
  - Phosphine residue can cause high background in subsequent samples



*SIMS of AlGaAs grown after  
Phosphorus contamination*

W.E.Hoke and P.J. Lemonias JVSTB **17**  
1999, p. 2009.

# SBIR research program lifetime

- SBIR Program Goals include
  - Stimulate technological innovation
  - **Use small business to meet Federal R/R&D needs**
- SBIR Phases
  - Phase I explores the feasibility of innovative concepts with awards up to \$250,000 and 12 months.
  - Phase II is the principal R&D effort, with awards up to \$1,600,000 and 2 years.
  - *Phase III: pursue commercial applications of their R&D with non-SBIR/STTR funding.*
    - Market for high polarization photocathode material is small
    - Commercialization not (yet?) financially viable



# Efforts to restore supply

- DOE Funding Opportunity 20-2310
  - MOCVD (*metal organic chemical vapor deposition*)
    - JLab: M. Poelker and M. Stutzman
    - BNL: E. Wang
    - ODU: S. Marsillac, B. Belfore
  - CBE (Chemical Beam Epitaxy)
    - JLab: M. Stutzman
    - UCSB: C. Palmstrøm, A. Engel
- MBE SSL GaAs/GaAsP Distributed Bragg Reflector
  - Sandia National Lab: Center for Integrated Nanotechnology
    - BNL: L. Cultrera
- Acken Optoelectronics Ltd., Suzhou China
  - Yiqiao Chen, formerly of SVT Associates
  - SSL GaAs/GaAsP photocathodes on order for evaluation





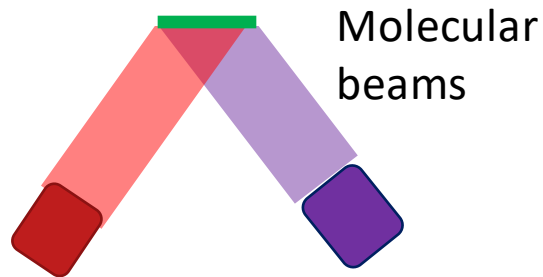
# MBE, GSMBE, CBE and MOCVD

## MBE

Gas Source  
Molecular Beam  
Epitaxy

elemental As, P, Ga

- Pressure  $\sim 10^{-8}$  mbar
- Growth rates  $\sim 1 \mu\text{m/hr}$
- Very precise control



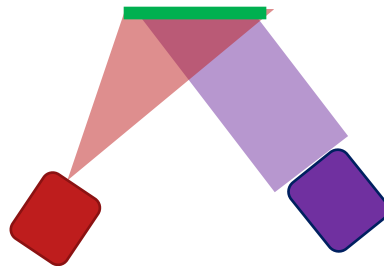
## GSMBE

Gas Source  
Molecular Beam  
Epitaxy

$\text{AsH}_3$ ,  $\text{PH}_3$ ,  
elemental Gallium

**Used at SVT**

Molecular  
and gas sources



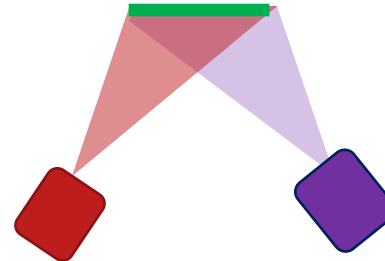
## CBE

Chemical Beam Epitaxy

$\text{AsH}_3$ ,  $\text{PH}_3$ , triethyl  
gallium (TEGa) or  
elemental Gallium

- Pressure  $< 10^{-4}$  mbar
- Growth rates  $0.5\text{--}1 \mu\text{m/hr}$

Low pressure  
gas sources



## MOCVD

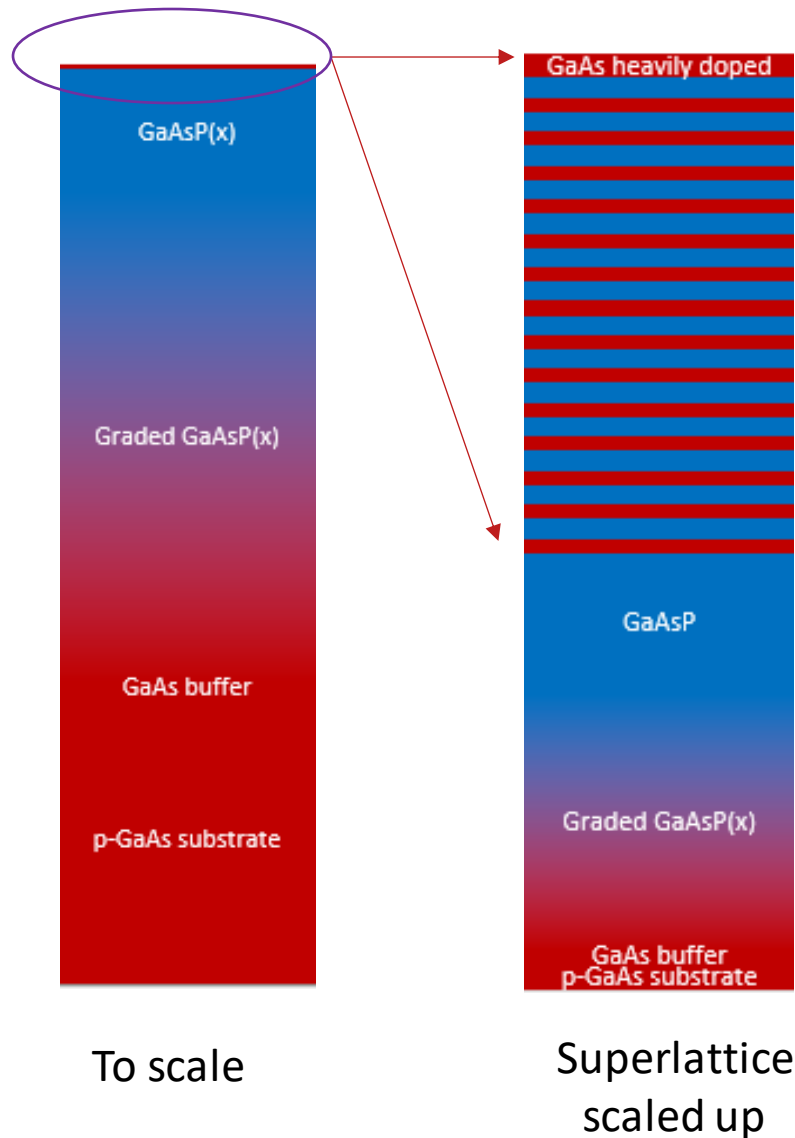
Metal organic chemical  
vapor deposition

$\text{AsH}_3$ ,  $\text{PH}_3$ , trimethylgallium  
(TMGa)

- Pressures  $> 100$  mbar during growth
- Growth Rates  $10 \mu\text{m/hr}$
- Traditionally difficult to get sharp interfaces



# Wafer growth



- Epitaxial Buffer Layer grown on GaAs
- Graded GaAs to  $\text{GaAs}_{(1-x)}\text{P}_x$
- $\text{GaAs}_{(1-x)}\text{P}_x$  layer
- Superlattice
- Heavily doped top layer

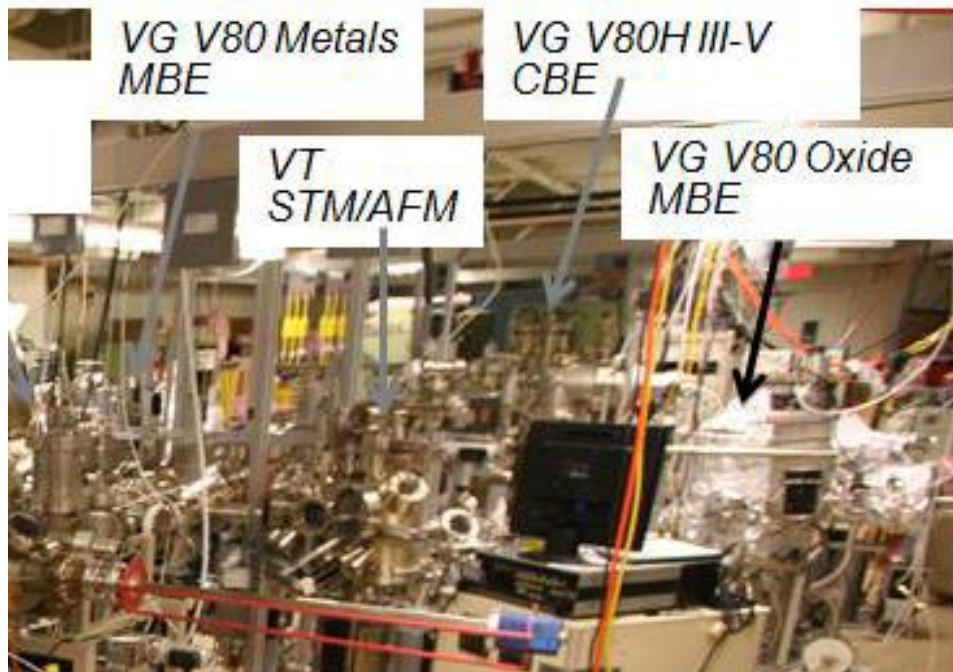
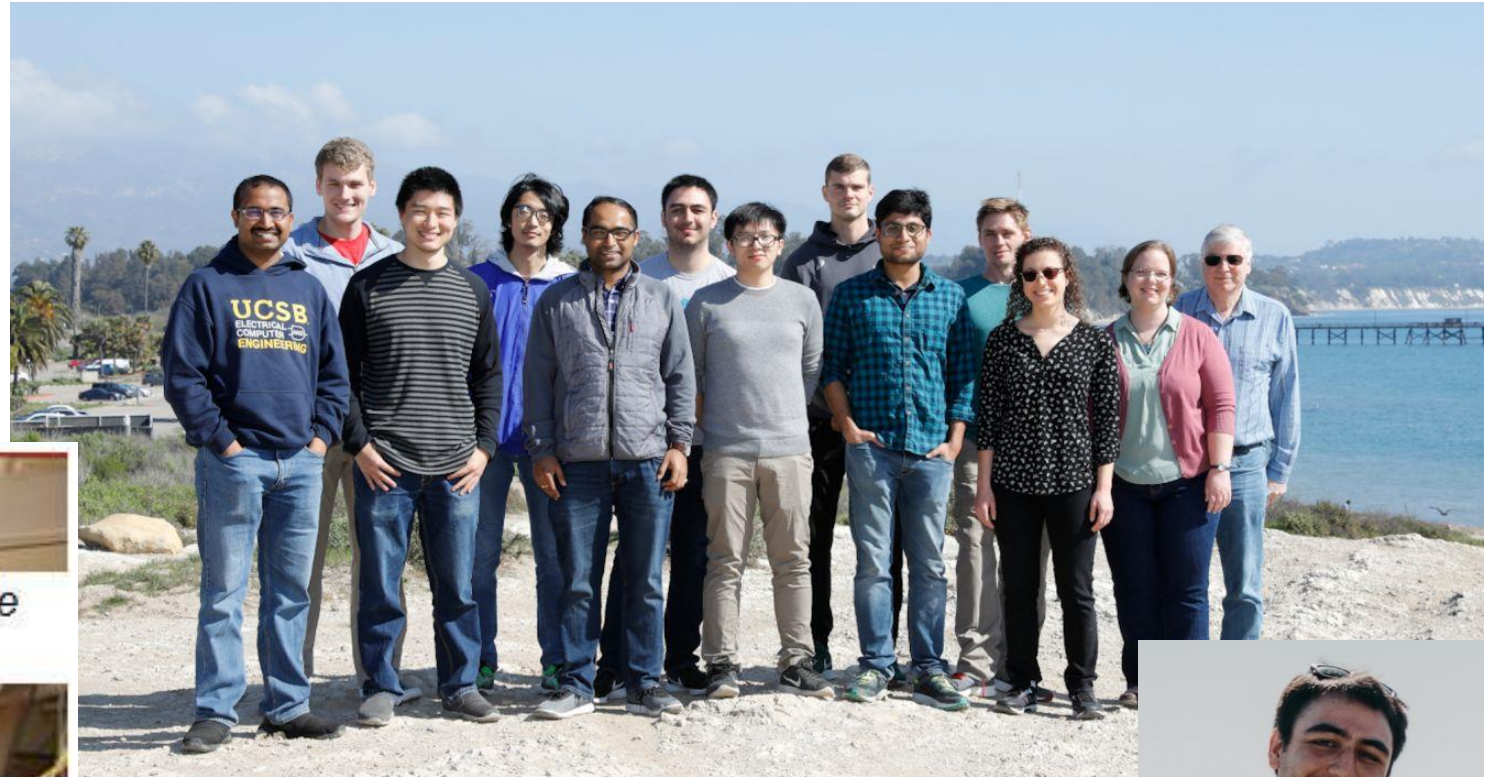
## Parameters to vary

- Substrate Temperature
- Source Temperature/Pressures
- Time
- Grading profile
- Underlying crystal orientation
- Superlattice layer thickness

# CBE: Photocathode progress

Chris Palmstrøm Group, UCSB

- Aaron Engel, graduate student
- Chemical Beam Epitaxy System

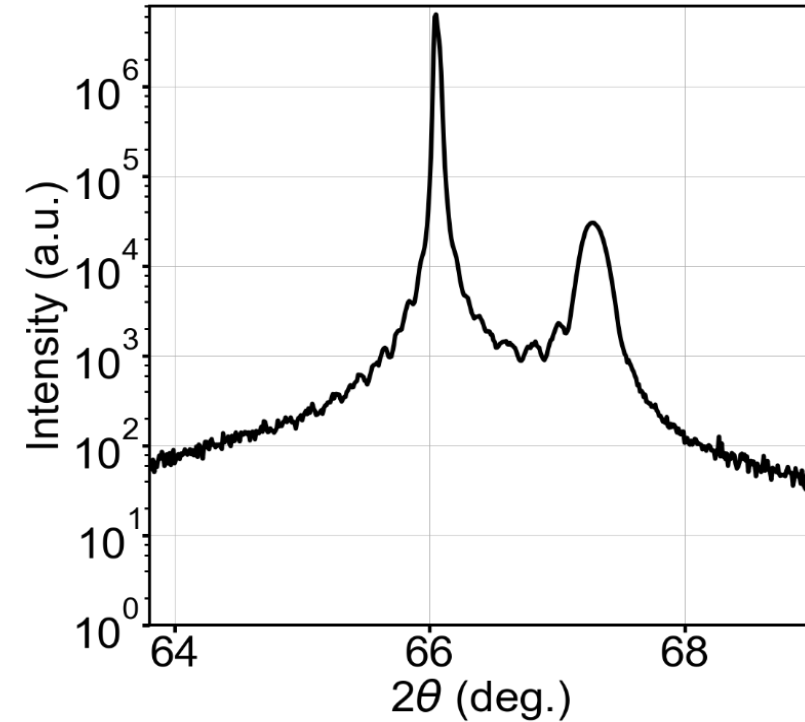
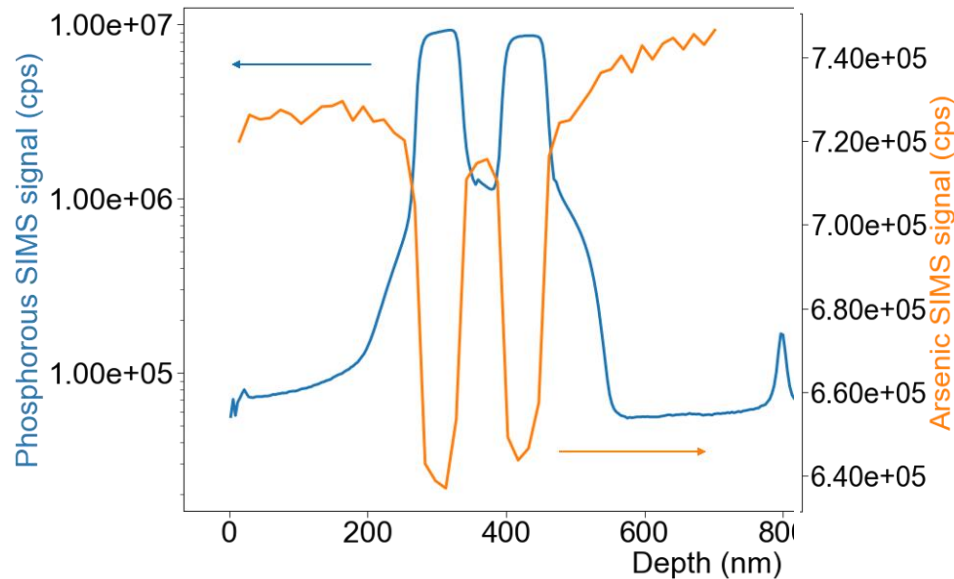


# CBE: Photocathode progress

- Computerized control developed for GaAs->GaAsP graded layer
- Interface quality between GaAs and GaAsP measured
  - SIMS analysis, x-ray diffraction
- Sample temperature, gas flux optimized for proper stoichiometry
- Testing strained GaAsP on GaAs initially

SIMS:  
Composition  
vs. Depth

GaAs:Be 250 nm
GaAs <sub>0.83</sub> P <sub>0.17</sub> :Be 50 nm
GaAs:Be 50 nm
GaAs <sub>0.83</sub> P <sub>0.17</sub> :Be 50 nm
GaAs:Be 4 μm
GaAs:Zn >10 <sup>18</sup>

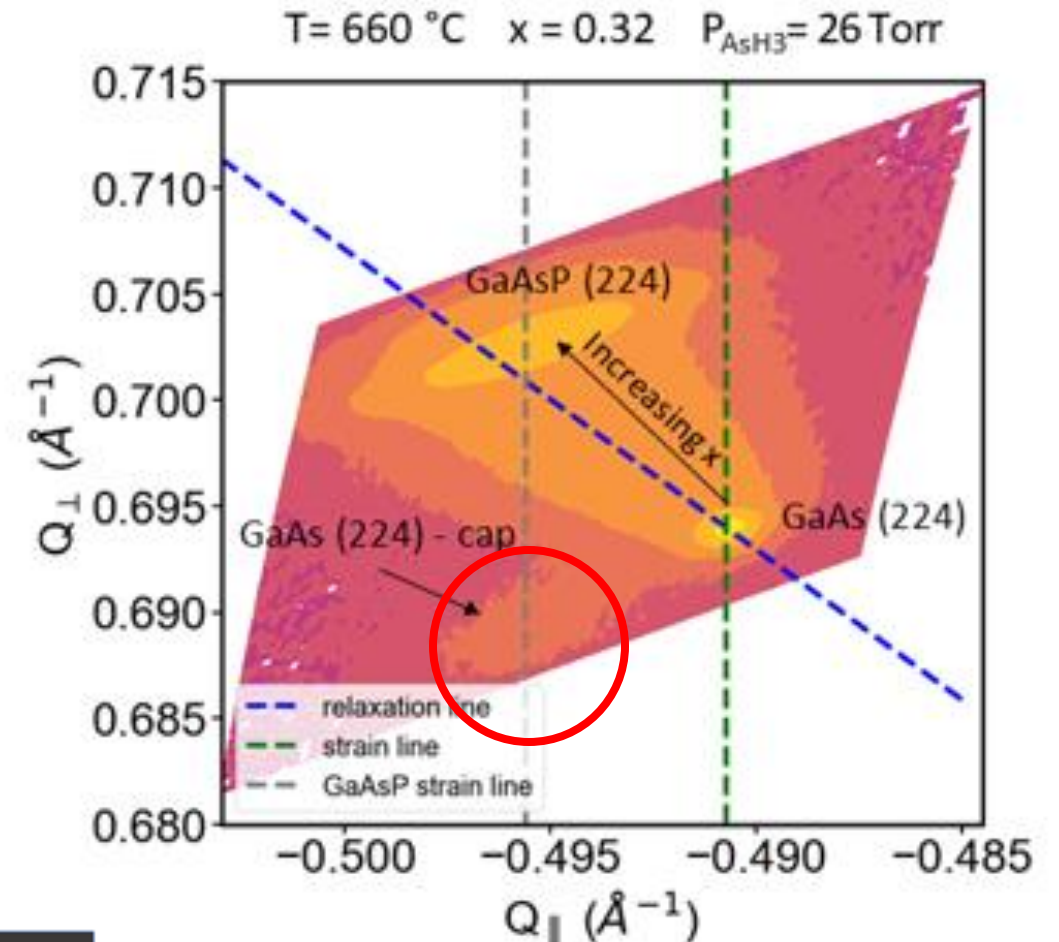
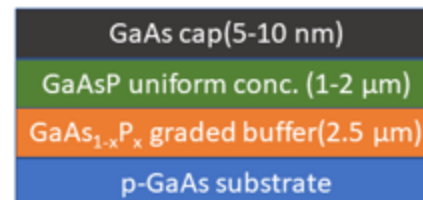


x-ray diffraction:  
1 micron GaAs<sub>0.75</sub>P<sub>0.25</sub> on GaAs  
Testing analysis tools for interfaces



# CBE: Photocathode progress

- Computerized control developed for GaAs->GaAsP graded layer
- Interface quality between GaAs and GaAsP measured
  - SIMS analysis,
- Sample temperature, gas flux optimized for proper stoichiometry
- X-ray Reciprocal space mapping
  - Plot of lattice distance during growth
  - Graded Layer with minimal strain
  - GaAs layer (5-10 nm) strained: lattice constant that of GaAsP



X-ray reciprocal space map for single 5-10 nm GaAs layer on GaAsPx

# CBE: Photocathode progress

## Next Steps

- Triethylgallium and phosphine create high vapor pressure background
  - Move to elemental Ga source?
  - Upgrade sample bonding from indium to gallium
- Grow photocathode material to test & test at JLab

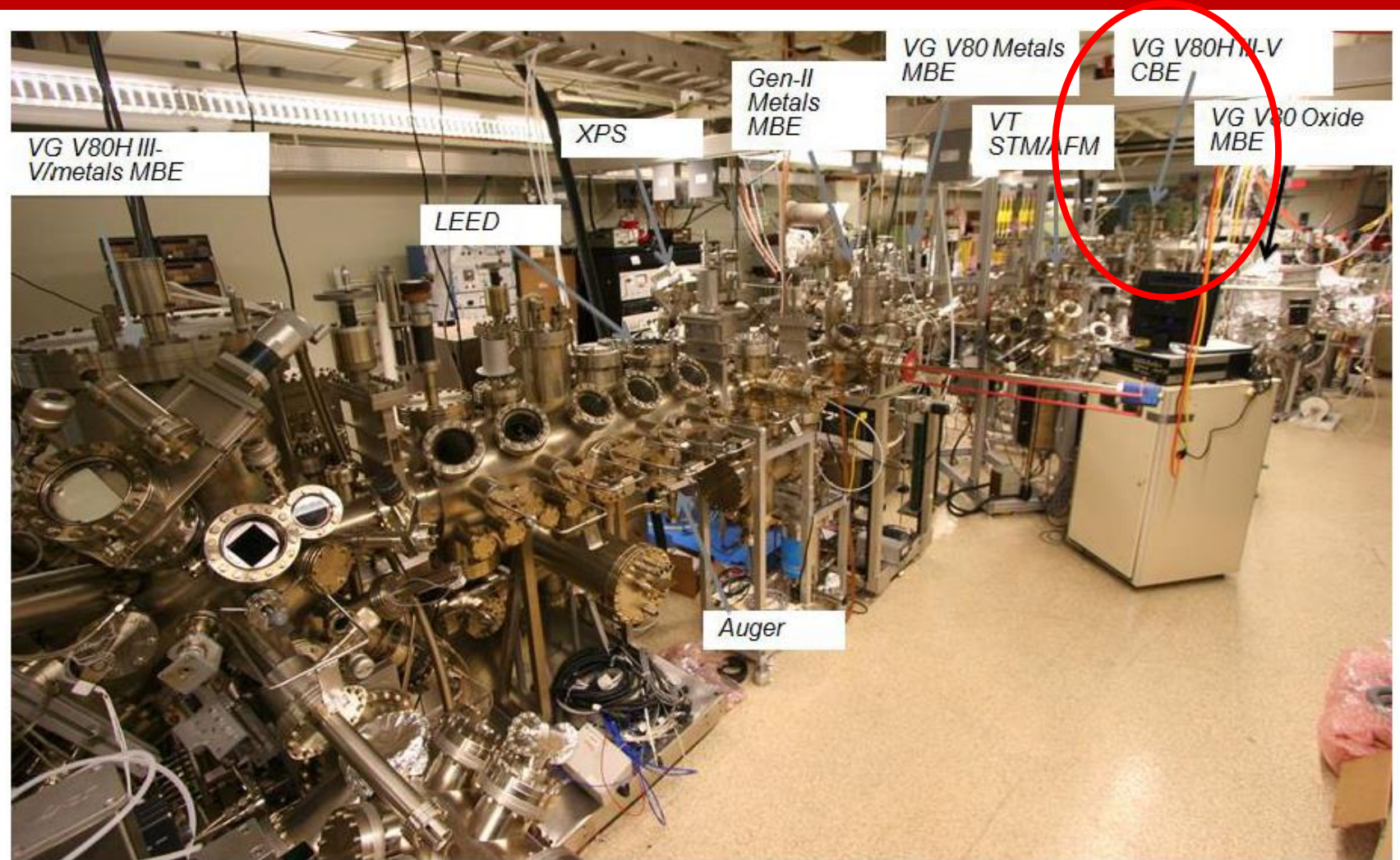


Figure 2 Semiconductor deposition system at Chris Palmstrom's lab at UCSB. The CBE system for the growth of this material is shown at the back and labelled "VG V80H III-V CBE".



# MOCVD: Photocathode progress

Virginia Center for Photovoltaics



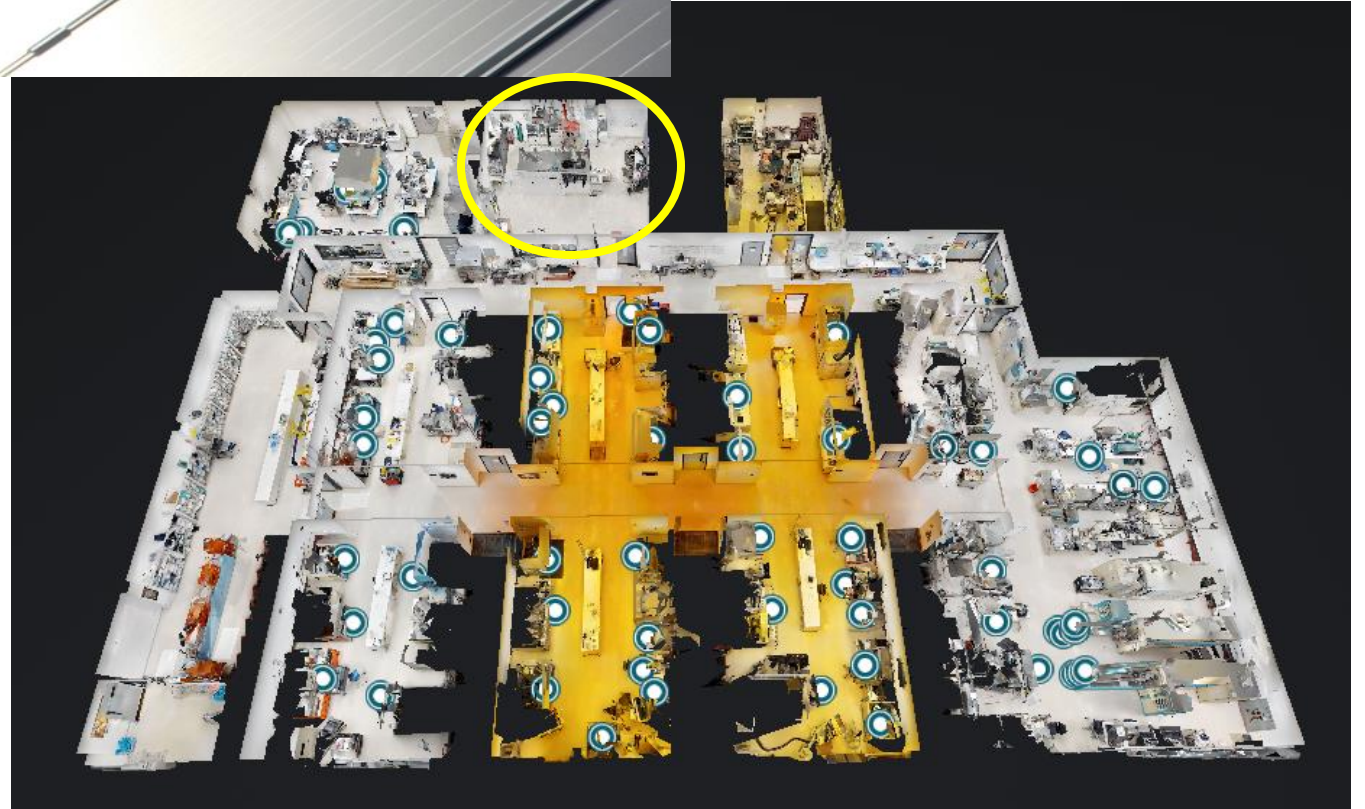
The Rochester Institute of Technology  
III-V EPICenter



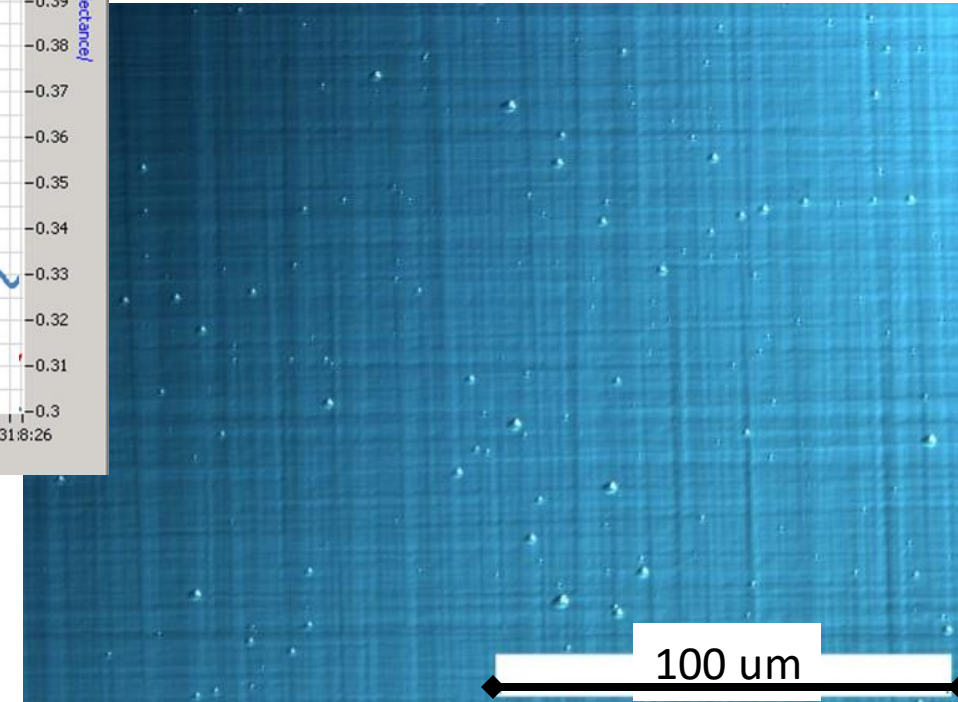
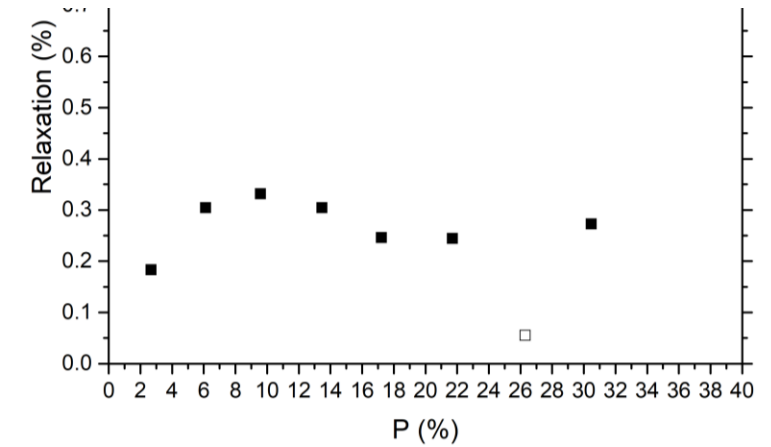
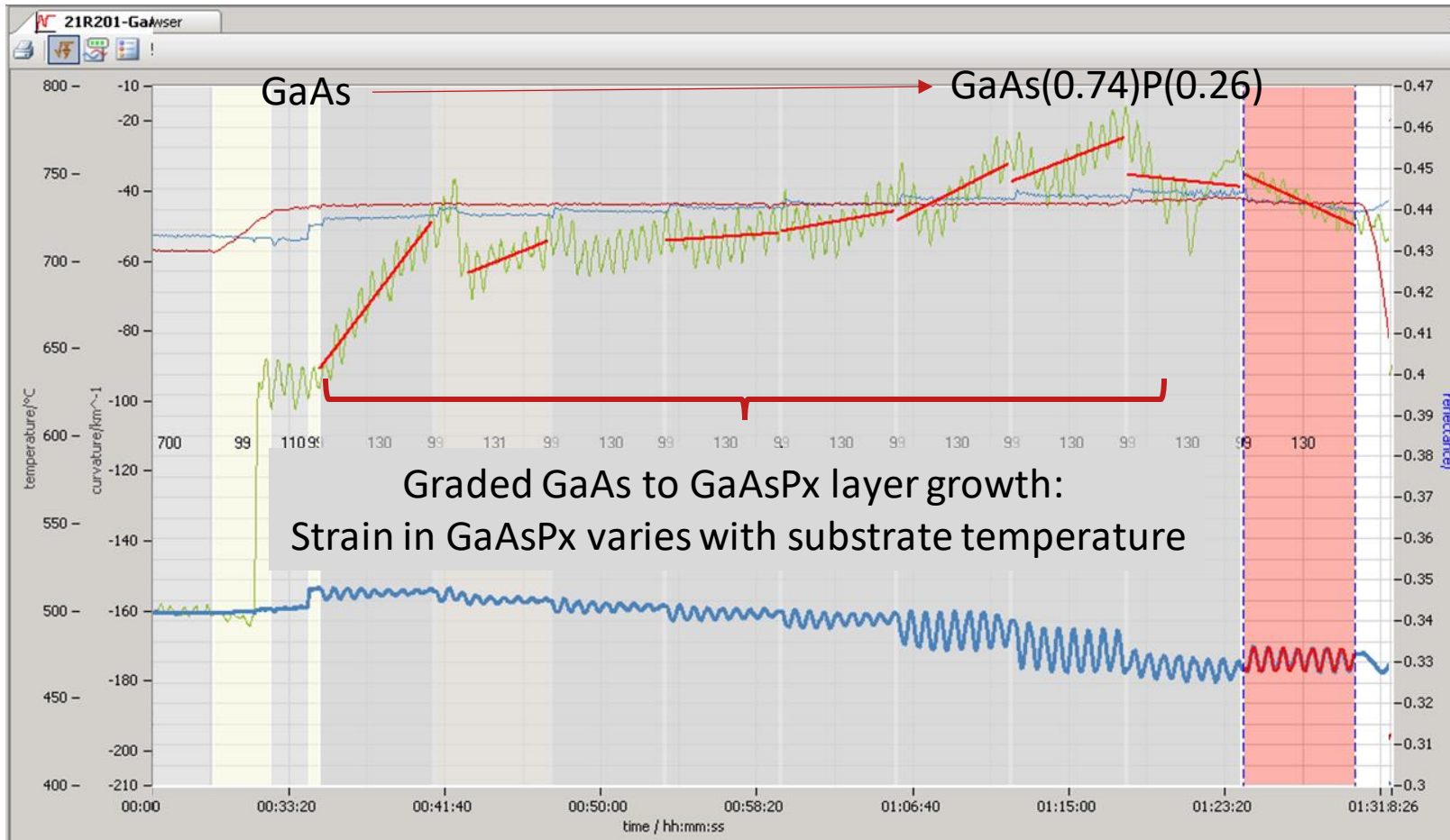
Dr. Sylvain Marsillac,  
Old Dominion University



Ben Belfore  
ODU Graduate  
Student



# Results: MOCVD



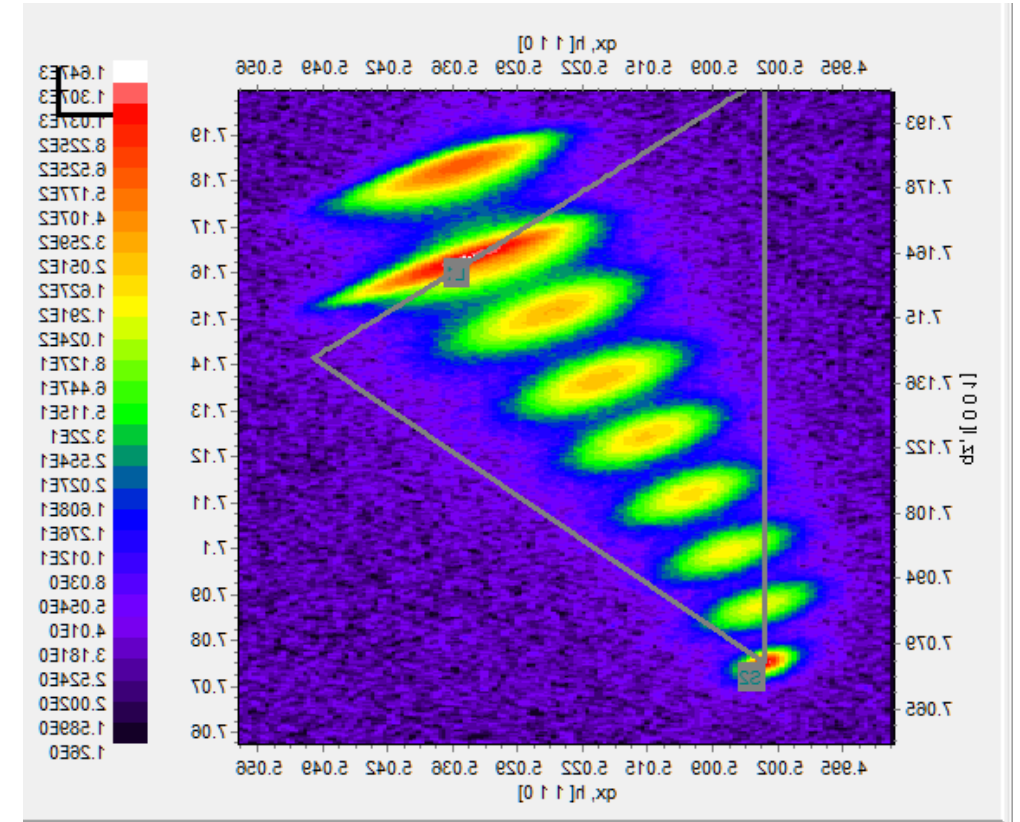
Higher temperatures yield improved surface  
with moderate relaxation throughout  
730°C growth temperature

Optimizing  
temperatures,  
graded layer profile



# Results: MOCVD photocathode progress

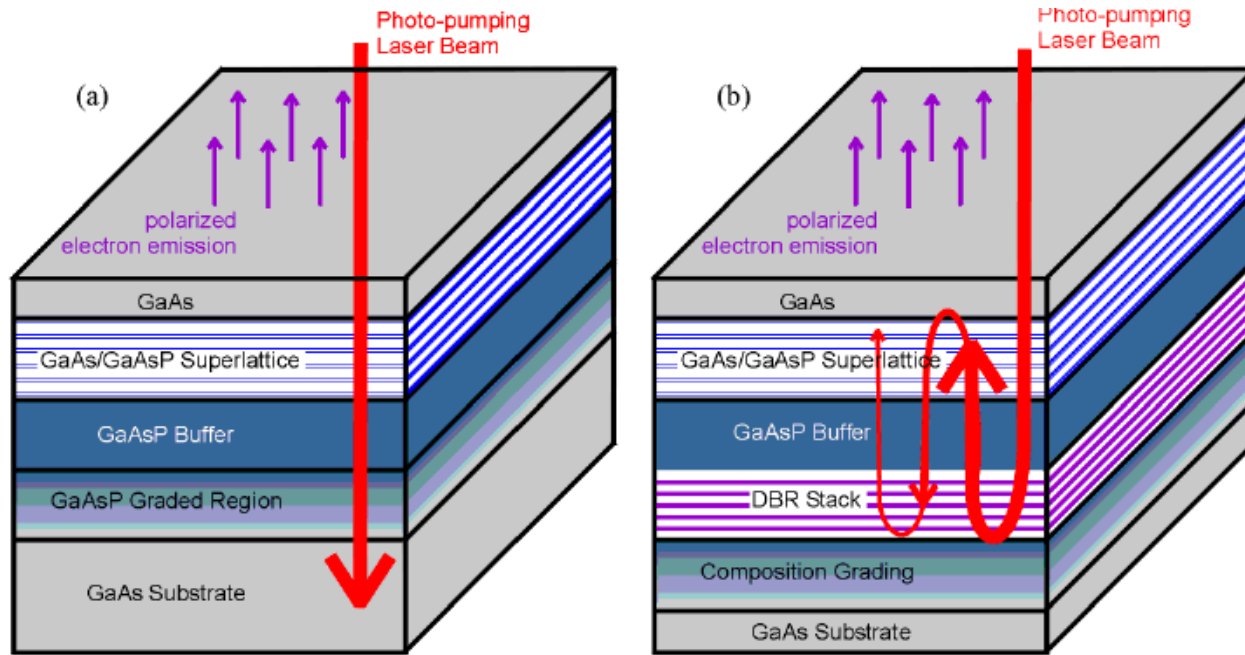
- Graded layer “metamorphic” test runs
  - Optimizing parameters for highest relaxation
  - Hall effect measurements for dopant characterization
- Superlattice runs
  - Growing superlattice on each metamorphic run
  - Optimizing parameters with zinc dopant
- Characterization
  - Surface analysis (SIMS, TEM) planned
  - **Ready for first polarization measurements**
  - JLab: MicroMott Polarimeter
  - BNL: Specs Mott Polarimeter
    - Operational, testing various samples



X-ray reciprocal space mapping

Crystal growth by Ben Belfore under the supervision of Sylvian Marsillac, Old Dominion University  
MOCVD system at Rochester Institute of Technology

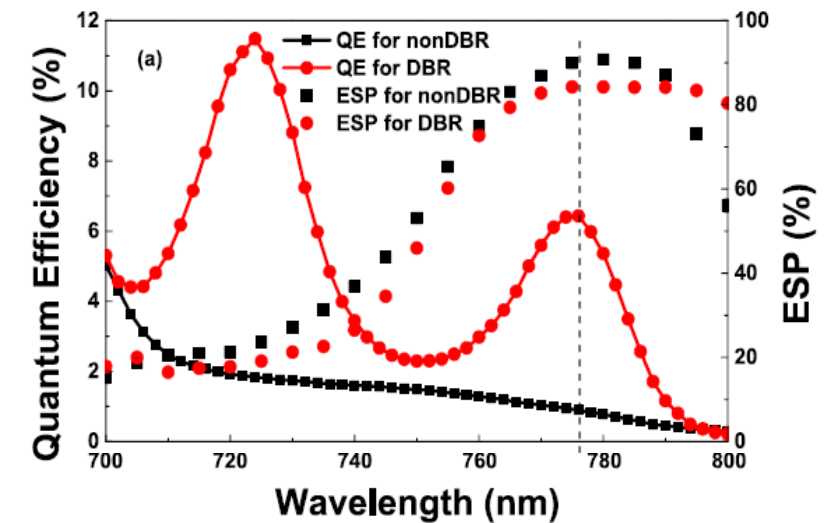
# Distributed Bragg Reflector



DBR structure has Fabry Perot structure

- Thickness tuned to desired wavelength
- Multiple passes -> more excited photons
- Polarization of light preserved

SVT DBR:  
Polarization >80%  
QE 6% (6x typical)

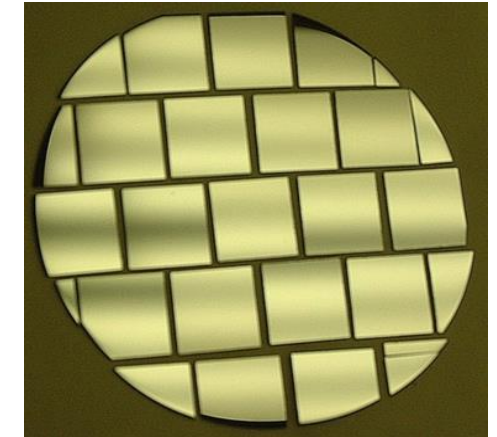
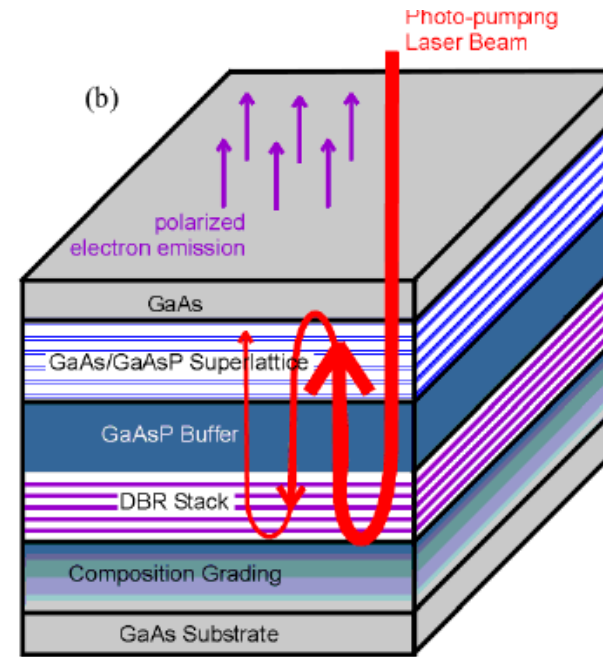


Wei Liu, Yiqiao Chen, Wentao Lu, Aaron Moy, Matt Poelker, Marcy Stutzman, and Shukui Zhang, "Record-level quantum efficiency from a high polarization strained GaAs/GaAsP superlattice photocathode with distributed Bragg reflector", Appl. Phys. Lett. **109**, 252104 (2016).

# Results: MBE DBR photocathode progress

- BNL: Luca Cultrera
  - Funding: Center for Integrated Nanotechnology
- Sandia National Lab
  - Several MBE growth systems
  - 3" wafers
- 240 nm Superlattice (vs. ~100 nm)
- First & second samples complete

GaAs	5 nm	$p = 5 \times 10^{19} \text{ cm}^{-3}$
GaAs/ GaAs <sub>0.62</sub> P <sub>0.38</sub> (30 pairs)	4/4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$
GaAs <sub>0.81</sub> P <sub>0.19</sub>	300 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
AlAs <sub>0.78</sub> P <sub>0.22</sub> /GaAs <sub>0.81</sub> P <sub>0.19</sub> (10 pairs)	65/55 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
GaAs <sub>0.81</sub> P <sub>0.19</sub>	2000 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
GaAs->GaAs <sub>0.81</sub> P <sub>0.19</sub>	2750 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
GaAs buffer	200 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
GaAs substrate		$p > 1 \times 10^{18} \text{ cm}^{-3}$



Representative diced GaAs wafer

BNL Mott polarimeter measurements

- Good QE (>1%)
- Polarization ~80%

Issues: non-uniformity across photocathode

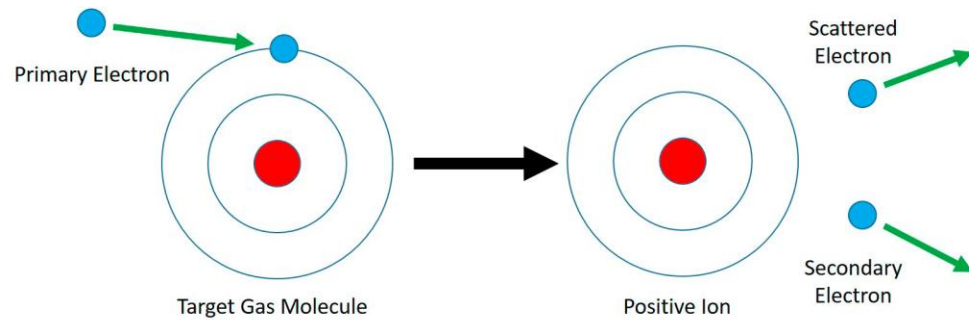
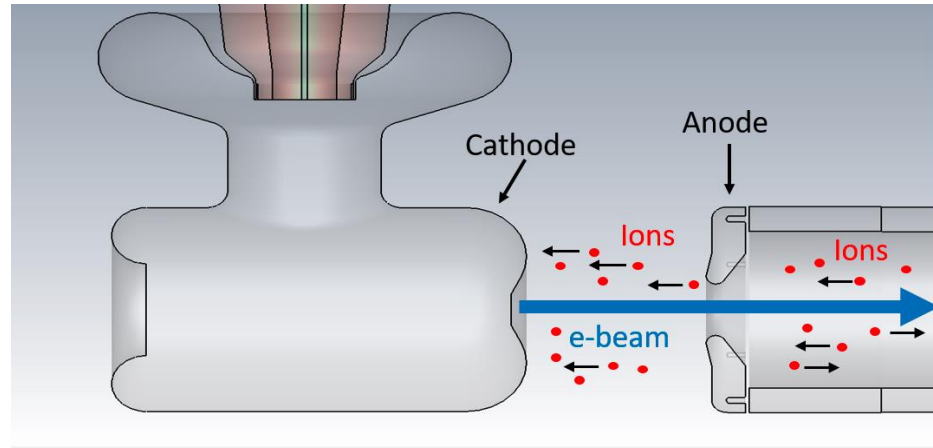
Future: Optimize and test

# Outline

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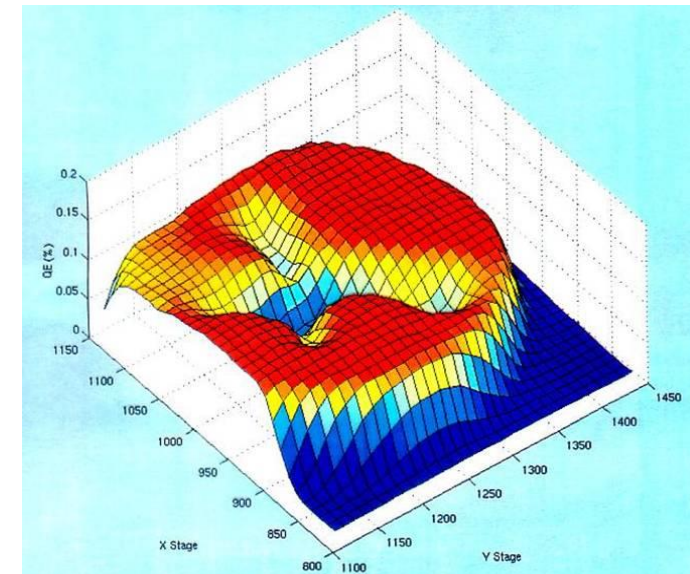
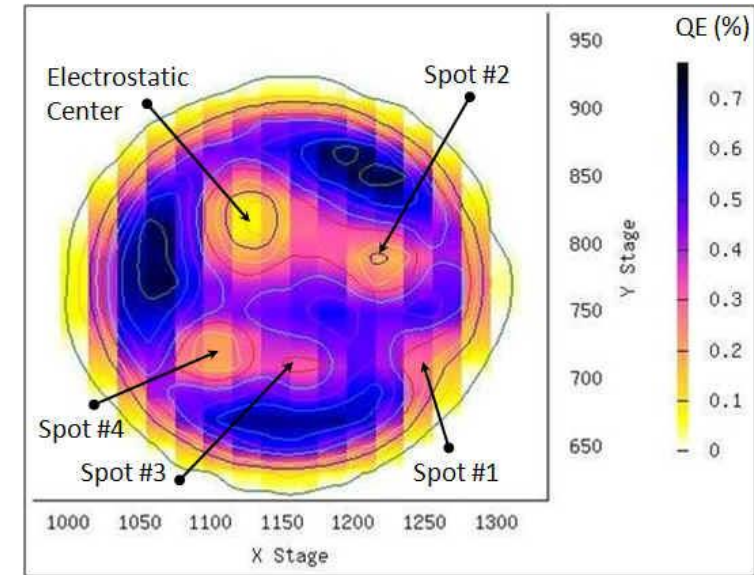
- Jefferson Lab, EIC and polarized electrons
- Photoemission from GaAs
- High polarization photocathodes
  - Structure
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  - Ion acceleration
  - Vacuum improvements
  - Damage evaluation
- Novel ideas for photocathodes
- Conclusions

# Photocathode Lifetime limitations: Ion back-bombardment



Ionized residual gas limits lifetime

1. Implantation/surface chemistry
2. Liberates gas: x-ray or secondary e-





# Photocathode Lifetime improvements: Vacuum system

## Installed pumping

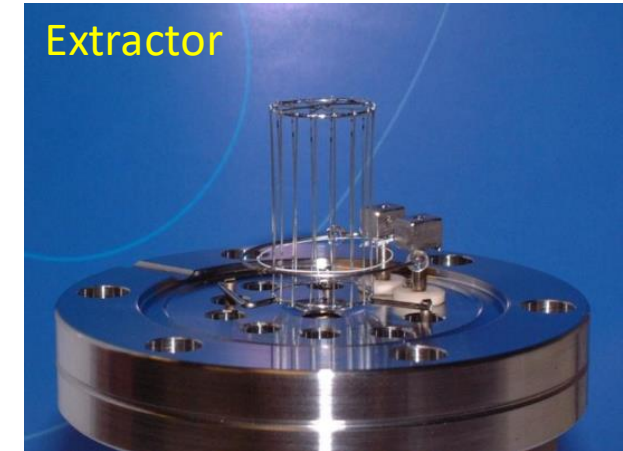
- SAES WP1250 modules x 10 (5600 L/s total)
- Gamma SEM/XHV ion pump (45 L/s)
- ~ 25 micron TiZrV coating

Measured pressure  $\sim 1.3 \times 10^{-10}$  Pa  
(extractor gauge, x-ray limit  
measured and subtracted)

Charge Lifetime:  **$\sim 200$  Coulombs**



NEG pumps & Anode in Gun



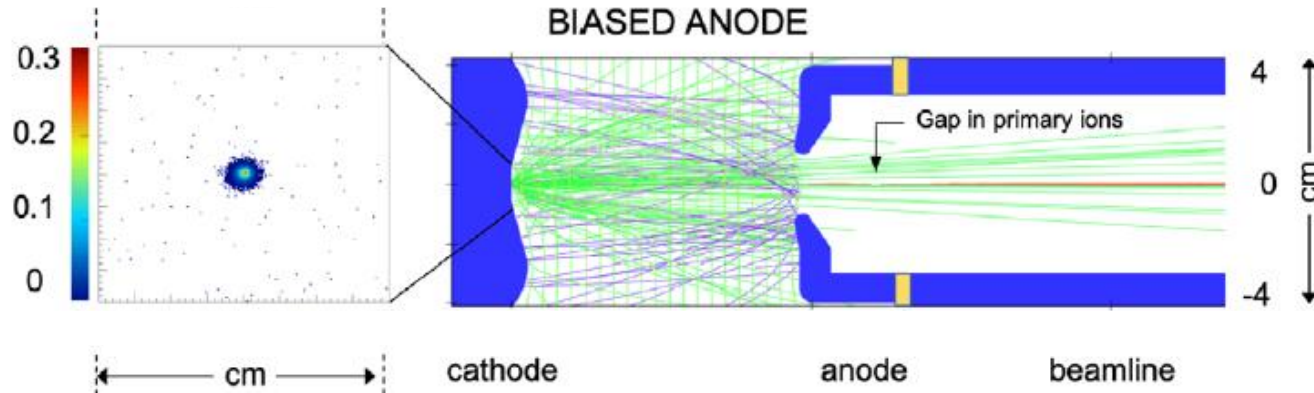
Extractor

Extractor gauge  
x-ray limit reduced  
through geometry  
Watanabe 3BG (Bent Belt  
Beam) gauge  
230° deflector BeCu  
housing  
JVSTA **28**, 486 (2010)

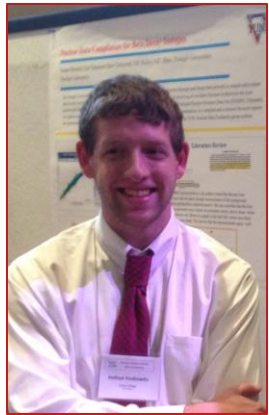


3BG

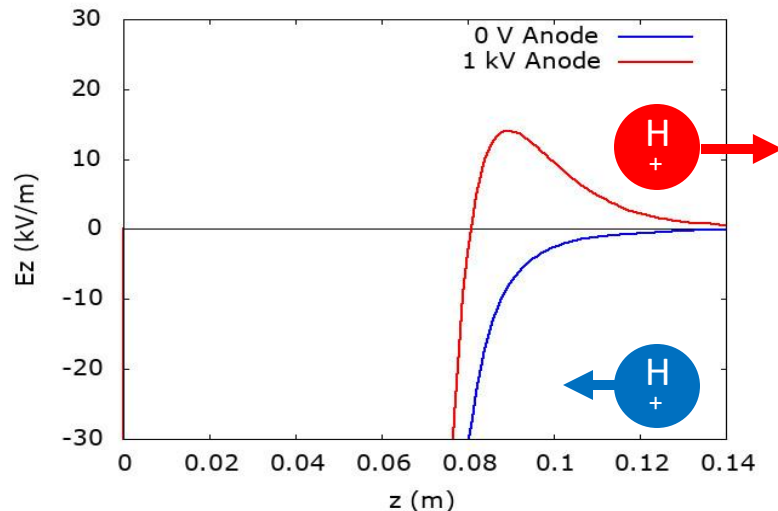
# Biased Anode for Lifetime Enhancement



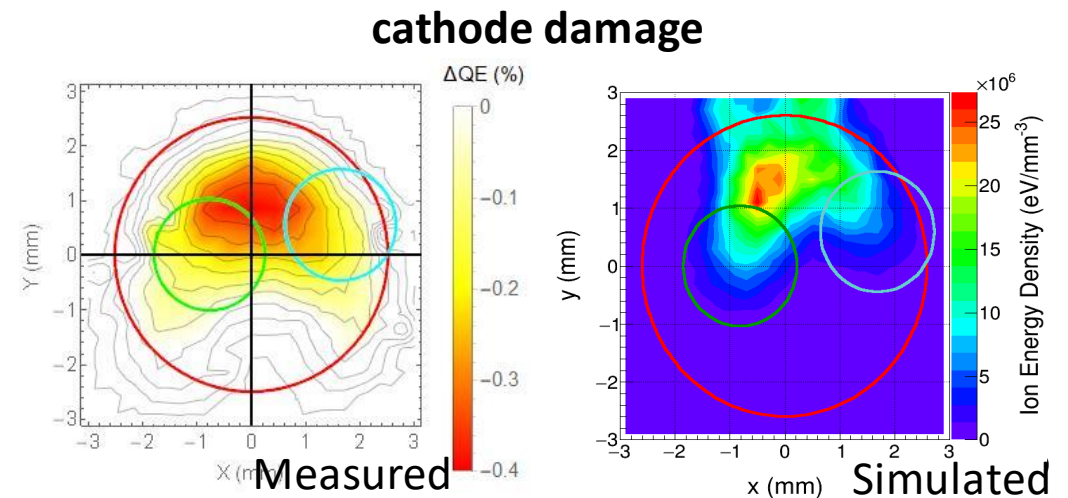
Simulations by C. Valerio in C. Hernandez-Garcia et al.,  
Phys. Rev. Accel. Beams **22**, 113401 (2019)



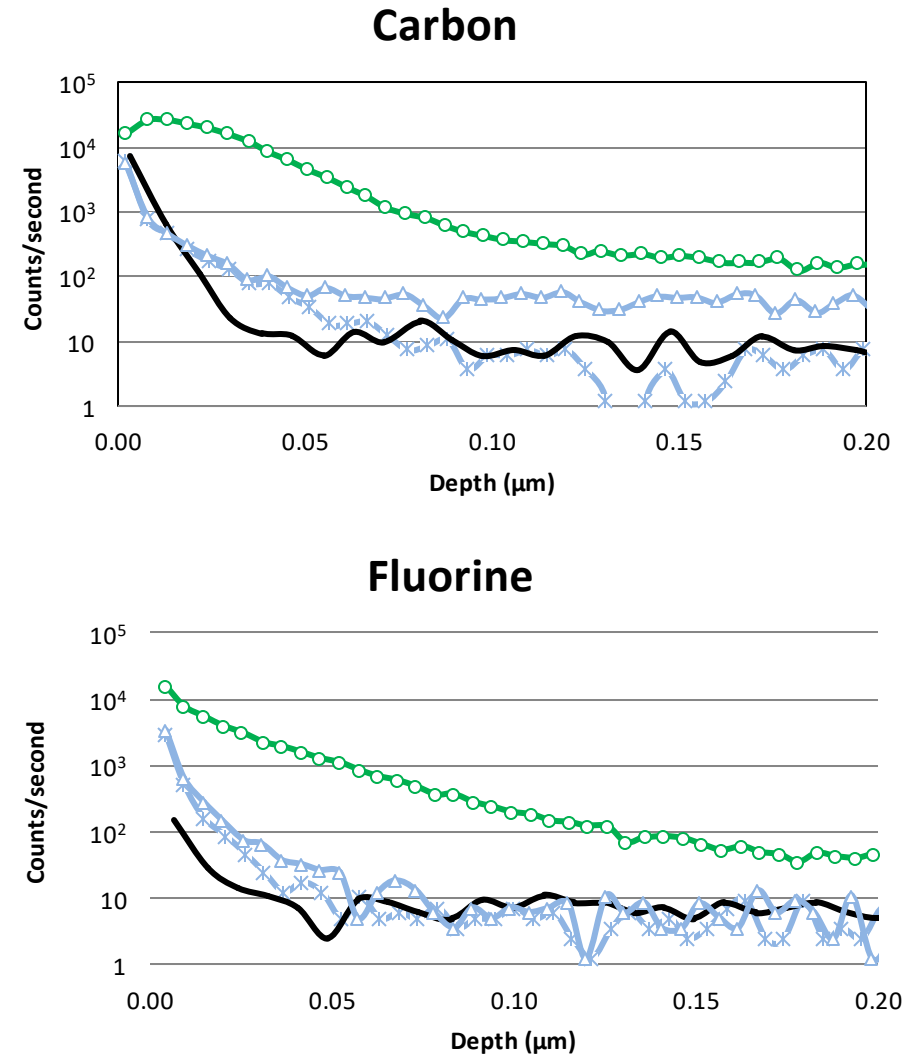
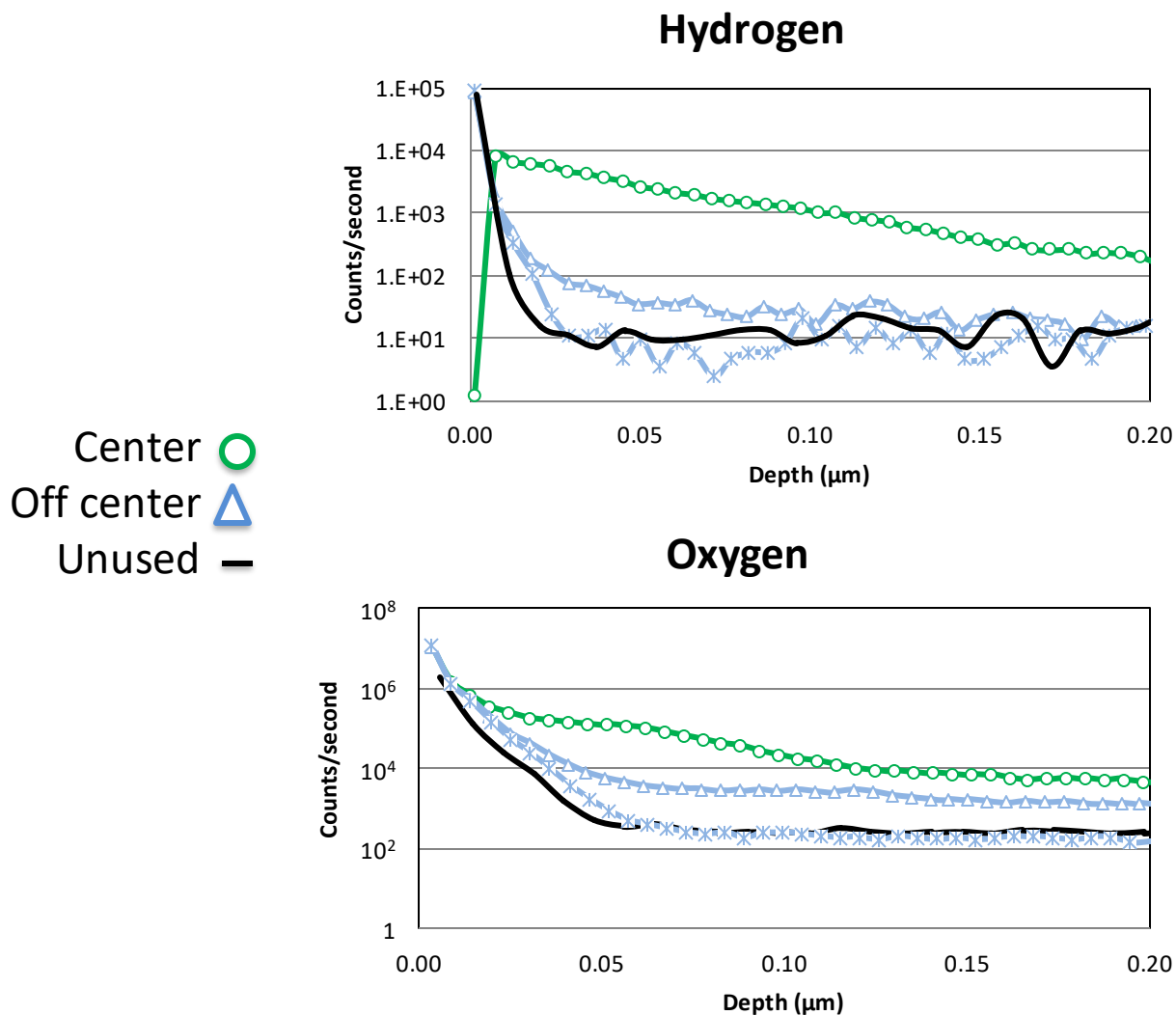
Josh Yoskowitz  
PhD thesis work



- Lifetime limitation: Ionized gas from beamline incident on photocathode
- Josh Yoskowitz, Ph.D. research  
Anode bias in CEBAF gun
  - Unbiased Lifetime < 200 Coulombs
  - Biased Lifetime **~300 Coulombs**
- Injector beamline rebuild 2021
  - Lifetime consistently over 250 C during 4 hall beam operation



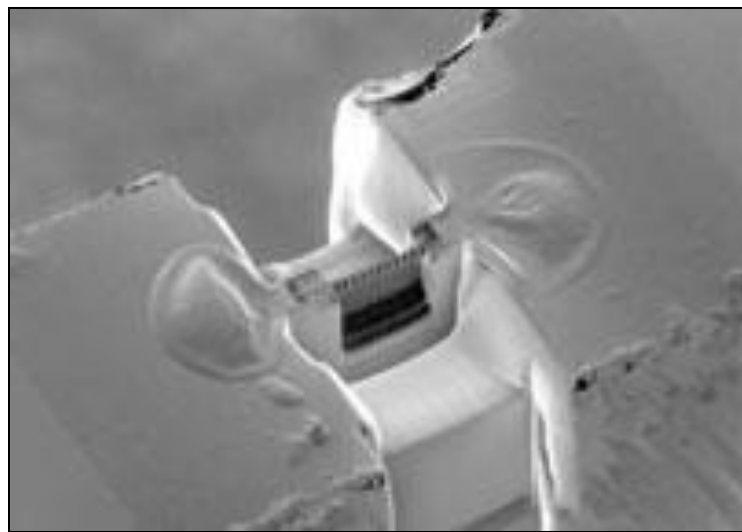
# Residual gas implantation: SIMS analysis



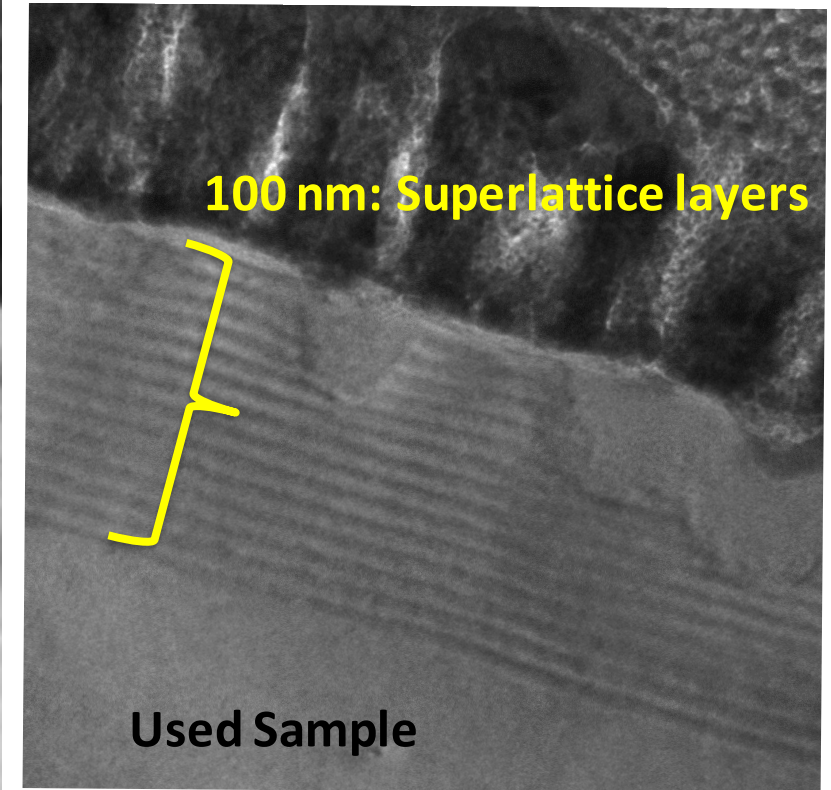
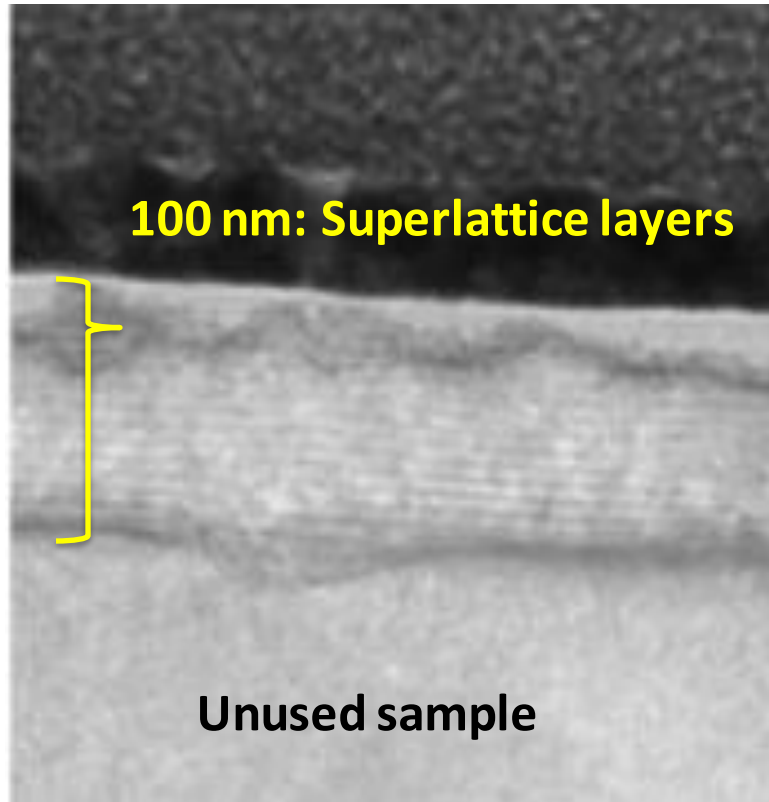
V. Shutthanandan, ..., M.L. Stutzman, et al., Surface science analysis of GaAs photocathodes following sustained electron beam delivery, PRSTAB **15** 063501 (2012)



# Liftout FIB / TEM analysis



F.A.Steve et al., Surf. Interface Anal. **31**, 345, (2001)



- Focused Ion Beam used to mill cross sectional depth profile for TEM
- Au/Pd evaporated, Pt sputtered to protect surface (misalignment = shadows)
- Uniform layers, no darkening

Obvious damage

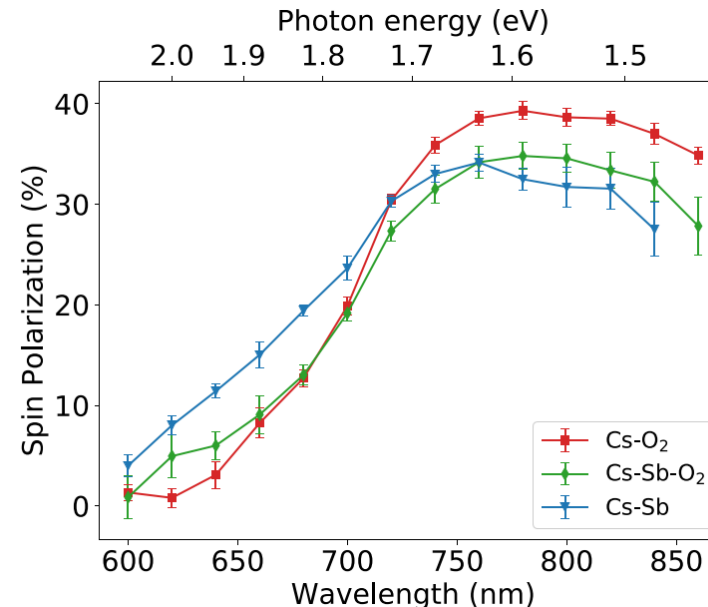
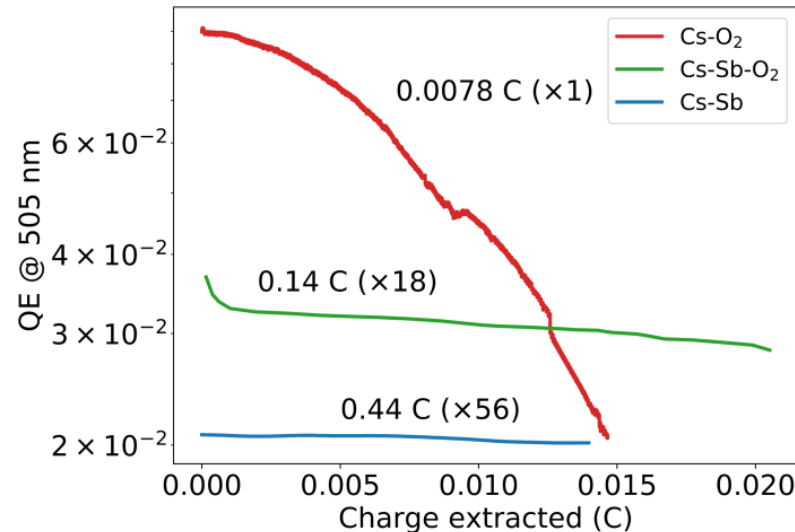
- Why non-uniform?
- Heat cycle vs. implantation role?

# Robust Activation for Lifetime Enhancement: Sb-Cs-O J.K. Bae, Cornell

- Typical Photocathode activation: Cs & O
  - Sensitive to vacuum conditions
- Antimony activations goals
  - Reduce vacuum sensitivity
  - Increase lifetime
  - Preserve QE and polarization
- Cs, Sb and O

**Jai Kwan Bae, Cornell**

Bae et al, *J. Appl. Phys* **127**, 124901 (2020)



## Cornell measurements

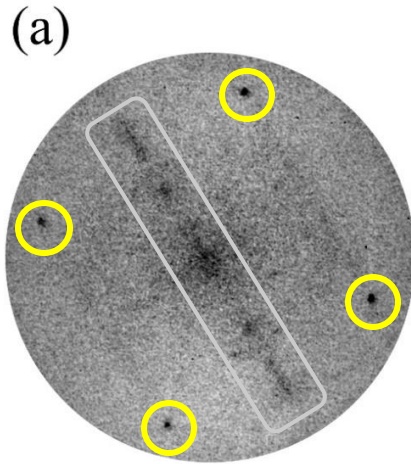
- Low voltage test stand
  - Vacuum not optimal
- Strained Superlattice and Bulk GaAs tested

## JLab collaboration

- High Voltage UTF tests
  - Polarization
  - Lifetime
  - Extreme High Vacuum
  - 200 keV Mott Polarimeter

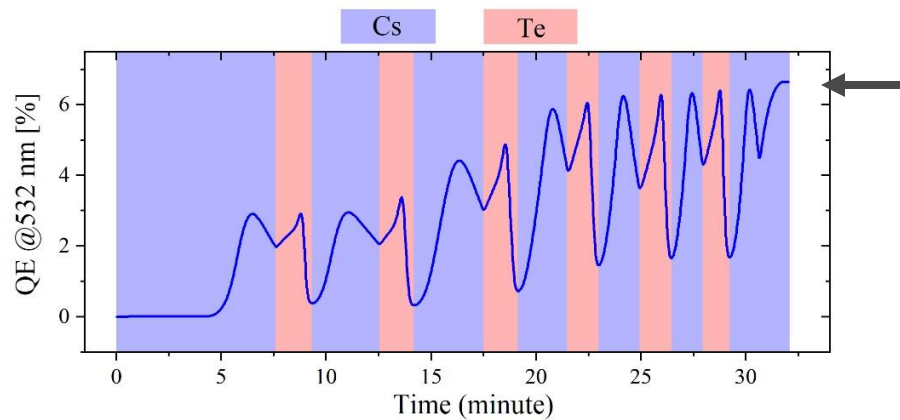


# Robust Activation for Lifetime Enhancement: $\text{Cs}_2\text{Te}$ , J. Biswas, BNL

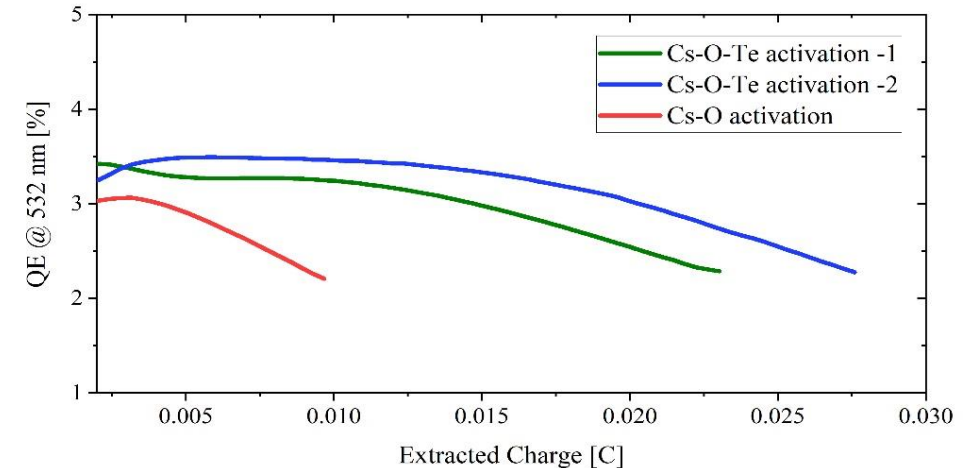


(1x1), & defused (4x6)  
reconstruction

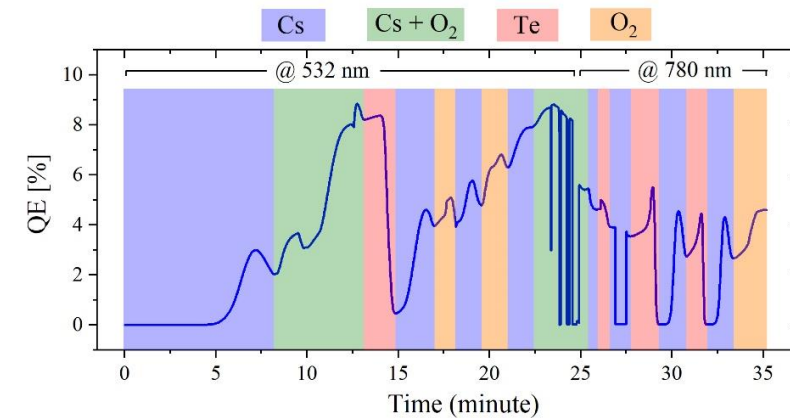
Oxide desorption – LEED



Cs-Te activation on GaAs



Longer charge lifetime in a test  
chamber as compared to Cs-O/GaAs



Cs-O-Te activation on GaAs

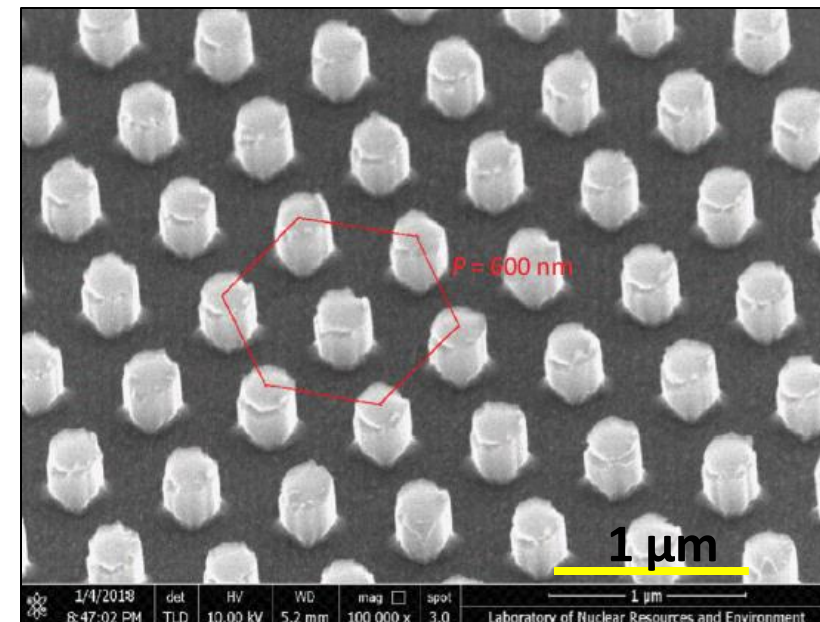
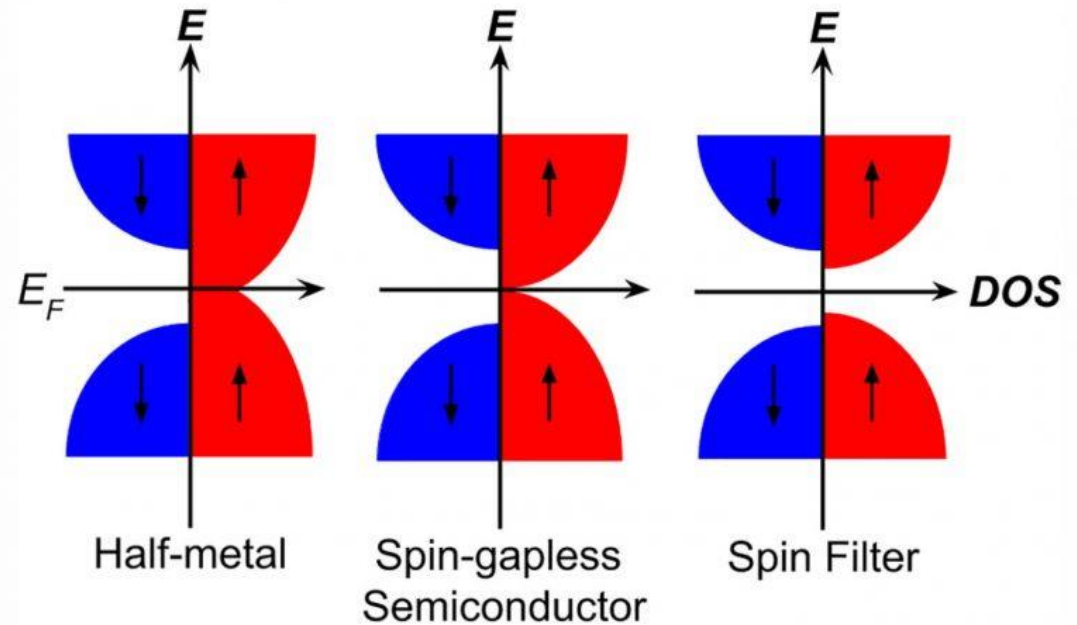
# Novel Polarized Photocathodes

## Spintronic materials

- Half metals
- Heusler alloy/ half-Heusler
  - Surface plasmon polaritons to enhance emission  
Z.Li et al., Scientific Reports 7(1):44335 (2017).
- Spin filters: Euclid Techlabs SBIR projects

## Nanopillar arrays: Goal: Enhanced QE

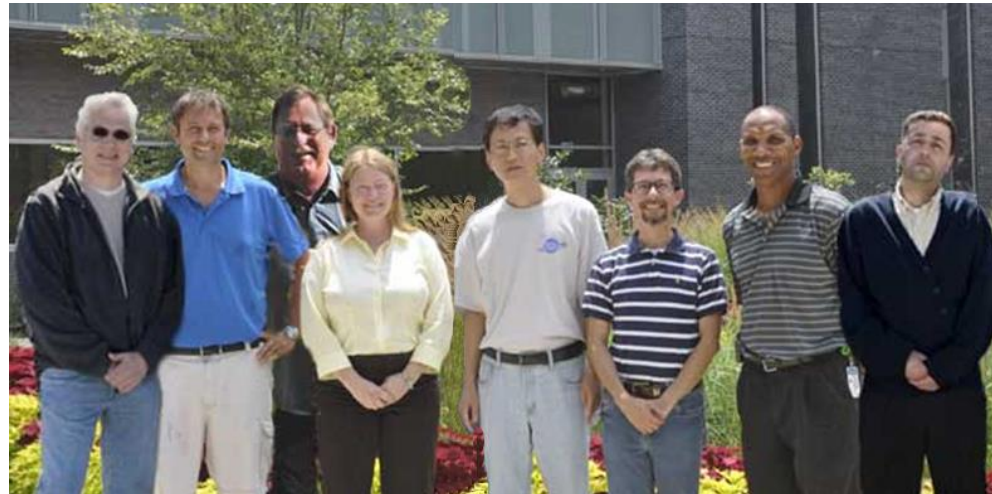
- X. Peng et al., Opt. Express **28**(2), 860-874 (2020)
- X. Peng et al., Phys. Rev. Applied **12**, 064002 (2019)



# Conclusions

- High polarization SSL photocathodes for nuclear physics accelerators
  - Supplier issues, new growth method initiatives, looking for industry or DOE partners
- Superlattice lifetime limitations
  - Vacuum improvements, biased anode, robust activations
- Novel photocathode materials
  - Spin filters, half-metals, nano-pillar arrays

Jefferson Lab  
Center for  
Injectors and  
Sources



Questions?

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